

# ElliCalc

# Manual

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# **1** Introduction

ElliCalc is an ellipsometric software to extract thickness and optical data from thin, transparent layers on different substrates. ElliCalc uses Ocean Optics / Mikropack microspectrometers.

ElliCalc offers a lot of different options like:

- Simulation and measurement of multilayer systems (weakly absorbing or transparent)
- A powerful software engine in the background ("SCOUT")
- Additionally: an easy-to-use "internal " mode for thickness extraction
- A graphical user interface that is very easy to use (recipes)
- Simulation of up to 10 layers (weakly absorbing or transparent)
- Highly accurate thickness measurements between some nanometers up to about 25 μm.
- Extraction of dispersion  $n(\lambda)$  and  $k(\lambda)$ , roughness, EMA-fractions and other layer parameters, if using SCOUT add-on
- 3D mapping mode with a motor driven xy(z)-stage (=function of position)
- Online/multipoint measurements (=function of time)
- Remote control via OLE-commands from external software
- Video
- Combination with reflectometry ("NanoCalc")

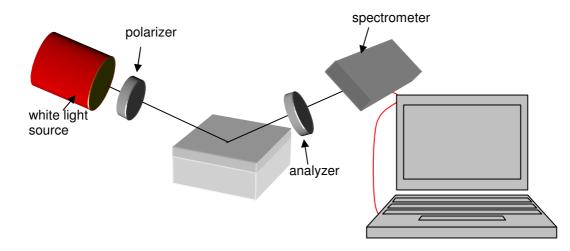
#### Measurement principle

A thin layer is illuminated with **white** light via a collimating optics and a spectrometer measures the <u>change of polarization</u> (that occurs after reflection) as a function of wavelength. ElliCalc software determines thickness (and optical parameters) of the layer.

The mathematics to extract useful data about the film is quite a lot, but the user is separated from these problems. The internally measured properties are called "Psi" and "Delta" (in degrees) or sometimes tan(Psi) and cos(Delta). Of course in spectroscopic ellipsometry these 2 properties are measured as a function of wavelength (in contrast to single wavelength ellipsometry)



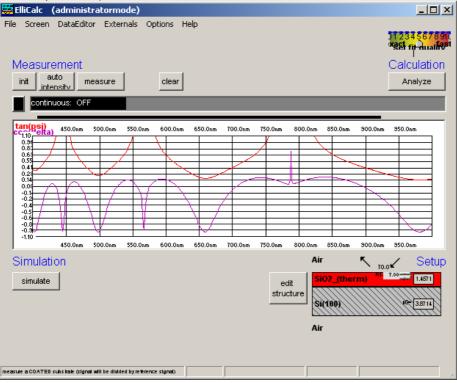
# 1.1 Measurement setup



A broadband white light source is focused on a thin layer under oblique incidence. The incoming light is polarized by a "polarizer", the reflected light is analyzed by an other polarizer. The intensity as a function of wavelength is measured by a spectrometer, a PC extracts the wanted information.

# 1.2 Measurement signal

The typical modulated signal of such a spectroscopic thin film measurement might look like this (after some data manipulations):

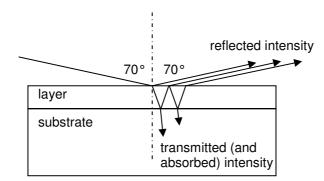


On the screen you see two different curves (fkor tan(psi) and cos(delta) as a function of wavelength. ElliCalc uses these signals to extract thicknesses and optical data for this (SiO<sub>2</sub>) layer on Si.

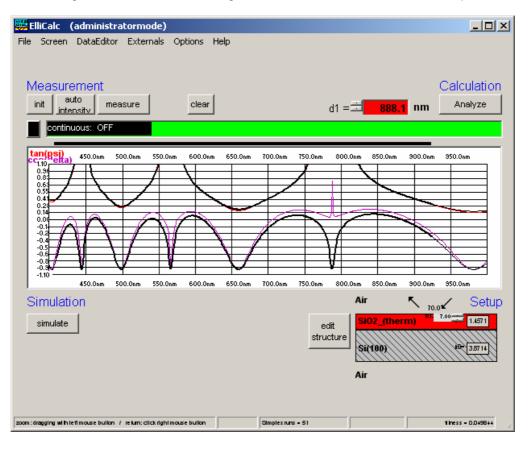


# 1.3 Physical principle

The measurement principle of ElliCalc is the well-known fact of oblique **reflection** and **interference** of light in thin layers. Light is reflected (and normally transmitted), resulting in different phase shifts and different intensities for different wavelengths. Ellipsometry measures the change of phases and intensities (between vertically and horizontally oriented light) and calculates different layer parameters like dispersion or thickness.



After some calculations ElliCalc will show a result (here: 888 nm) nm as the best fit to the experimental data (blue and magenta curves=measured signals, black curves = theoretical curves):





# 2 Installation

ElliCalc is delivered on a CD-ROM.

Insert the CD-ROM in your CD-ROM drive, use Microsoft Explorer to run "ElliCalc-Setup.exe". Do not call "ElliCalc.exe" at this level, if you happen to find it in some subdirectory.

ElliCalc will ask you for a directory (and propose a directory "c:\programs\ElliCalc").

If you prefer other names, change this to "c:\MyPrograms\ElliCalc" or any convenient directory name). Reboot the PC after installation.

#### **Deinstallation:**

If you want to deinstall ElliCalc from your computer, go to "system control", "software" and deinstall ElliCalc. Do **NOT** just delete it because ElliCalc adds some files to your windows\system directory !! Always de-install the software properly.

# 3 Product support

Please contact your local distributor for product support. Here you can find additional information: <u>www.mikropack.de</u>



# 4 Getting started

After installation of your hardware and software you should be ready to make your first measurements.

#### An example:

- For the first steps it is a good idea to use a special "<u>step wafer</u>" with different oxide thicknesses. You can use this wafer to check the correct functionalty of the ellipsometer. Please ask your hardware supplier for information about step wafers. Otherwise use a really well known sample with good optical properties (not rough, homogenous,
  - Otherwise use a really well known sample with good optical properties (not rough, homogenous, simple layer structure, like SiO2 on Si)
- 2. Choose a room without to much light, avoid full sunlight and reflections (you might run into problems with stray light).
- 3. Load a layer recipe (via "files/load layer recipe") corresponding to your sample, e.g. "SiO2 on Si.Irc". Then the structure in Setup picture shows a correct layer system

Öffnen	<u>?×</u>			
Suchen in: 🗀 Layer_Recipes	- 🖬 🍅 🖬 -	Air	κ	Setup
no_recipe.lrc	Si3N4 (table) on Si.lrc		N 70.0' 🖌	
PolySi on Cauchy2 on Cauchy1 on glass.lrc		8:02	Imierenl	
PolySi on Cauchy2 on Cauchy1 on Si.lrc	SiO2 (table) on Si.lrc	3102	[micron]	
PolySi on SiO2 (table) on glass.lrc	TiO2 (table) on glass.lrc			,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,
PolySi on SiO2 (table) on Si.lrc	💻 TiO2 (table) on Si.lrc			
Si3N4 (table) on glass.lrc	Universal Oxide on glass.lrc	Siler	vst.)	
			<b>V3</b>	
	<u> </u>			
Dateiname: SiO2 (table) on Si.Irc	open this file	Air		
Dateityp: Irc-file(*.Irc)	▼ cancel	All		
, , , .				

- 9. Now click on the button "measure"
- 10. The integrations times had been chosen <u>automatically</u> so that the maximum signal height is about 75% of the maximum to avoid saturation. If you change your sample now or later and the new sample has a different reflectivity you have to press the button "auto intensity". If the new sample is of the same type as before this is not necessary but advisable. Now you see the measured data with the typical interference wiggles.
- 11. Then click on the button "analyze" and wait for the result. You should get meaningful results.

File Screen DataEditor Externals Options Help			<u>_     ×</u>
Measurement int acto measure clear continuous: OFF	d1 =	= <mark>888.1</mark> nm	Calculation Analyze
Transformer 50.0mm 5		.0m 850.0m 900.0m	350.0nm
Simulation simulate	edit structure	SIO2_(ulerin)	0€ Setup 1.451 4€ 38714
zoom : dragging with left mouse buildin / refum: click right mouse buildin	Simplex runs = 51		1hess - 0.0+98++



# 5 Usermodes of ElliCalc

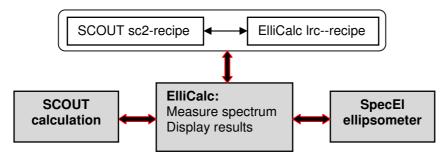
ElliCalc has two different usermodes, the "SCOUT-mode" and the "ElliCalc internal mode". At the moment the "SCOUT-mode" is the normal mode, the "internal mode" can only extract thicknesses and no dispersion

The "SCOUT-mode" requires that another software, called "SCOUT" is installed on this PC, the "internal mode" only uses ElliCalc.

# 5.1 SCOUT mode

ElliCalc works as a graphical user interface for a sophisticated film software "SCOUT" working in the background.

The whole process is necessarily driven by recipes.

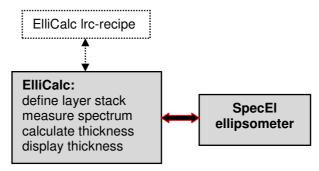


- within ElliCalc you have to load a "recipe", e.g. "SiO2 on Si.Irc". This ASCII-readable
  recipe contains a link to a SCOUT recipe like "SiO2 on Si.sc2". All necessary layer
  informations are contained in this SCOUT recipe and are read by ElliCalc, but only for
  display purposes.
- ElliCalc now controls the hardware, measures the sample and sends the measured Psi/Delta-values to SCOUT (via a file EC\_Data.xy in directory "ElliCalc\Internal\_Files").
- SCOUT does the calculation of all parameters
- the results are given back to ElliCalc via OLE-connection. The main fit parameters (thickness, refraction, absorption, roughness and EMA-fractions) are displayed by ElliCalc, as well as all other SCOUT fit parameters.

This SCOUT mode relies totally on good SCOUT recipes. So there must be someone (you or the administrator or Mikropack) in the background being familiar with the details and the physics of SCOUT. The advantage is a "one-button-ellipsometry" for the user and an enormous calculation power !

# 5.2 Internal mode

In this internal mode the user can create own layer stacks and does not need the external SCOUT software at all. There is no need to work with recipes, but is is recommended. BUT: At the moment <u>only</u> <u>thickness values</u> can be extracted, in one of the next releases also dispersion extraction is possible (not as exact as SCOUT, but maybe good enough)





# 5.3 Combiversion with NanoCalc

If you bought a combiversion ElliCalc + NanoCalc (= ellipsometry and reflectometry) you will see an extra menu "version". Here you can switch from one application to the other.

🐺 ElliCalc (loaded recipe=SiO2 (table) on Si) (administratormode)	
File Screen Options Version Help	
Nanocalc_1	
Nanocalc_10nk	Scout
Measurement Ellicale	Calculation
init auto measure clear	Analyze
continuous mode:	
tan(psi) ccciteta) 450.0nm 500.0nm 550.0nm 600.0nm 650.0nm 700.0nm 750.0nm 800.0nm 850.0nm 900.0nm	950.0nm
0.87	
0.60	
-0.20	
-0.43	
-0.60	
-0.81 -1.00 450.0nm 500.0nm 550.0nm 600.0nm 650.0nm 700.0nm 750.0nm 800.0nm 850.0nm 900.0nm	350.0nm
Simulation SCOUT c:\eigene dateien\na IIX Air 🤨	🖌 Setup
File Undate Objects Range Start Stop	.0¥ 0010 <i>p</i>
simulate Fit parameter set Actions Tools ?	
Method Import Start Export Mer#Vorseoc Si (Cryst.)	
Air	
Selected graph: R A E	
Continuous measurement is useful for adjusting your lamp in Ellipsometry spect	



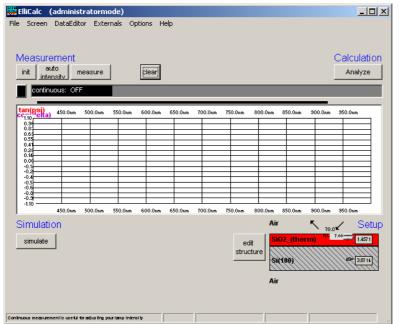
# 5.4 List of all menus and buttons

Main menu	Sub-menu	SCOUT mode	Internal mode
FILES menu	Load Scout layer recipe	Х	х
	Load ElliCalc layer recipe		
	Save as layer recipe		х
	Change layer recipe	Х	
	Export raw data	х	х
	Import raw data	Х	х
	Show SCOUT results	Х	
	Exit	Х	х
SCREEN menu	Spectrometer data	Х	Х
	Limits	Х	х
	Dispersion	Х	х
	Psi/Delta or tan(Psi)/cos(Delta)	Х	
EXTERNALS	Mapping	Х	х
	Analyze mapped data	Х	х
	Online/multipoint	Х	х
	Analyze online data	Х	х
	RS232	Х	х
	Video camera	Х	х
	Show plot	Х	х
OPTIONS	Change buttons	Х	х
	Roughness	(x)	х
	Data manipulations		х
	Fit parameters		х
	Some setups ElliCalc (motor steps)	Х	х
	Some setups SCOUT (stoptime)	Х	
	Some setups (change colors)	Х	х
VERSION	NanoCalc 1	х	х
	NanoCalc_10nk	х	х
HELP	Contents	х	х
	About	х	х
EDIT STRUCTURE			х



# 6 Basic features of ElliCalc

# 6.1 Init



This button performs 2 tasks:

- initialize the motors for polarizer and analyzer (e.g. end positions)
- automatically set the integration times to good values (so there is no need to press "auto intensity" directly after an init procedure).

#### hint:

If you change your sample you may run into saturation of the spectrometer = a (nearly) horizontal part in some of the measured curves near to the upper limit of the plot.

# 6.2 Auto intensity

This option automatically adjusts integration times.

This button has to be pressed if you use a completely different sample (each sample has a different reflectivity, so a different integration time). Normaly the "init button" already has performed such an auto intensity procedure.

If your sample is of the same type as your last sample (=has nearly the same reflectivity) it is not necessary to press this button.

AutoIntensity tries to get 75% of the maximum allowed value.

# 6.3 Simulate

This routine simulates a spectrum.

- in SCOUT-mode: from the .sc2-layer recipe data within SCOUT
- in ElliCalc internal mode: from the data in EditStructure (identical to the data in Thinfilm.ini-file)

#### Hint:

If you want to have a short check which structure is simulated at the moment, put the mouse cursor over the appropriate layer for some seconds and you see the layer thickness.



OR:

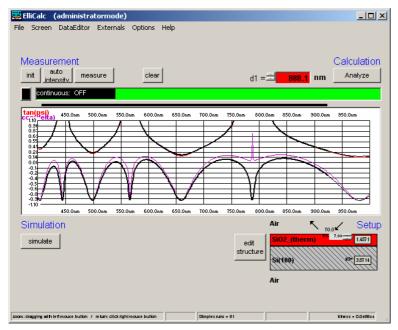
Leave your mouse cursor for some seconds over the button SIMULATE and look at the text in the status bar.

# 6.4 Measure

This routine measures the ellipsometric spectra of your test device.

If you use a double spectrometer, you had to adjust the crossover wavelength. Below this wavelength the data are collected from channel A ("master spectrometer"), above this wavelength they are collected from channel B ("slave spectrometer").

# 6.5 Analyze



This routine analyzes a spectrum (either simulated or measured) within the data extraction limits.

- In SCOUT-mode: SCOUT is doing the calculations. The structure that is simulated may only be changed within SCOUT.
- In ElliCalc's internal mode: ElliCalc is doing the calculations (only thickness at the moment)

#### Hint:

To have a short check which structure is simulated at the moment, put the mouse cursor over the appropriate layer for some seconds and you see the layer thickness. OR:

Leave your mouse cursor for some seconds over the button SIMULATE and look at the text in the status bar.

# 6.6 Continuous mode

The continuous button switches between continuous mode (=red button) and "stop continuous" (button =black). Then there will be a continuous measurement of the signal (necessary to adjust the height and tilt of your stage !!)

All others buttons of ElliCalc are disabled until you finish the continuous mode.

# 6.7 Fitness

Any extraction of parameters is accompanied by a value of "fitness". This is the sum of the mean square deviations between measured and simulated curve (normalized to the range of extraction). The fitness is a rough guide whether your thickness value is "good" or not.

In the file "Thinfilm.ini" you will find 3 entries in section [fit]: Failure\_RedLevel=1 Failure\_YellowLevel=0.1 RYG\_LevelsAreDisplayed=False



If you change the variable RYG\_LevelsAreDisplayed from "False" to "True" (in main menu

"Fitparameters"), the usual rainbow pattern on the screen will disappear and a simple color will show up.

- If the fitness is below Failure\_YellowLevel=0.1 you will see a GREEN color.
- If the fitness is between Failure\_YellowLevel=0.1 and Failure\_RedLevel=1 you will see a YELLOW color.
- If the fitness is above Failure\_RedLevel=0.1 you will see a RED color

#### Attention:

If you measure very thick layers (with a good correlation between maxima positions, but bad correlation between signal heights) you may end up with high values of fitness, but nevertheless the thickness results may be o.k.



# 7 Detailed features of ElliCalc

In this chapter the most common commands and menus of ElliCalc are decribed. Special commands and menus for "SCOUT mode" and for ElliCalc's "internal mode" are decribed in later chapters.

# 7.1 Main menu "File"

Internal mode	SCOUT mode
File Screen DataEditor External	Is File Screen Externals Options Ve
Load Scout layer recipe Load ElliCalc layer recipe	Load Scout layer recipe Load ElliCalc layer recipe
Export raw data	Change layer recipe
Import raw data	Export raw data
Print report	Import raw data
Exit Ctrl+X	Print report
	Show Scout results
	Exit Ctrl+X

# 7.1.1 Load layer recipe

This routine loads a layer recipe that has been saved earlier (extension: .lrc). Do not change the extension .lrc.

In SCOUT mode you may either load another SCOUT recipe ("load Scout layer recipe") or you may switch to ElliCalcs internal mode ("Load Ellicalc layer recipe"). See the screenshots above. In SCOUT mode all buttons captions are in *italic*, otherwise in normal.

It is assumed that <u>all</u> .lrc-files are in the default directory "ElliCalc\recipes\layer\_recipes", but you can change the directory path to any other directory on your PC (provided that you did not use "UseLast-Filenames\_EC=False" in section [Filenames\_EC] in Thinfilm.ini).

Öffnen 🥂						
Suchen in:	🗀 Layer_Recipes		≝			
💽 no_recipe.	lrc	📄 Si3N4 (table) oi	n Si.lrc			
PolySi on C	auchy2 on Cauchy1 on glass.lrc	SiO2 (table) on	glass.lrc			
PolySi on C	auchy2 on Cauchy1 on Si.lrc	🗾 SiO2 (table) on	Sillro			
💽 PolySi on S	iiO2 (table) on glass.lrc	TiO2 (table) on glass.lrc				
💽 PolySi on S	iiO2 (table) on Si.lrc	🖹 TiO2 (table) on Si.lrc				
💽 Si3N4 (tab	le) on glass.lrc	💽 Universal Oxide	e on glass.lrc			
•			Þ			
Dateiname:	SiO2 (table) on Si.Irc		open this file			
Dateityp:	Irc-file(*.lrc)	•	cancel			

There is a section [Scout] in this layer recipe with an entry for "Scout\_Recipename\_EC". This entry is a **link** to the corresponding SCOUT .sc2-recipe in the directory "c:\programs\scout\scout\_sc2\_recipes" (or similar directory name).



If this linked .sc2-recipe is existent, SCOUT will be used for calculations = "SCOUT mode".. If this link is empty, ElliCalc will calculate without SCOUT = "internal mode" (at the moment only for thicknesses !)

Example for SCOUT-mode (in ellipsometry):

[Scout] Scout\_DirPath=c:\programs\scout ScoutStopTime=15 Scout\_RecipeName\_NC= Scout\_RecipeName\_EC=SiO2 (table) on Si.sc2

Example for ElliCalc internal mode:

[Scout] Scout\_DirPath=c:\programs\scout ScoutStopTime=15 Scout\_RecipeName\_NC= Scout\_RecipeName\_EC=

The \*.lrc-file is an ASCII file that contains most parameters of the software, but NO measured or simulated values of psi/delta (or tan(psi) /cos(delta)) as a function of the wavelength.

If you load a recipe you will not see any curve on the screen, but a change in the setup or the limits.

#### 7.1.2 Print report

This routine allows you to enter some user data (names of operator, of sample and so on), shows a preview and prints on the Windows standard printer. Changing the printer is possible only within Windows itself.

Entering of user data: you may also change the names of the labels (empty labels: this line is not shown on the final print). In the preview window you may zoom in and out. After pressing the print button you have the chance to change some printer options.

If you want to get a printout of the complete screen or parts of it:

It is recommended to use a hardcopy program to print the different parts of the software with enough options to change colors, resolution etc.

We recommend a shareware "HC.EXE" (<u>http://www.sw4you.de</u> and on the CD-ROM in : tools\general), which will include a small button in every (!) window of your system near to the close button.

For online-users: we recommend to buy the OPTION ElliCalc-Online for printouts of Multipoint Measurement, Result-Windows with Statistic Data's and Excel-Connection.

#### 7.1.3 Show Scout report

(SCOUT mode only) See chapter "Special features for SCOUT mode

#### 7.1.4 Import raw data

(internal mode and SCOUT mode)

You are asked for an import- directory. The imported values are displayed in blue (=similar to measured values). The scale of the screen is not adjusted.

#### 7.1.5 Export raw data

(internal mode and SCOUT mode)

If a curve was produced by simulation or measurement it may be exported as ASCC-file ("raw data"). This file has a very simple structure: (lambda, tan(Psi), cos(Delta) 350,0.796,0.064



351,0.780,0.050 352,0.764,0.034 353,0.749,0.014 354,0.736,-0.009 355,0.722,-0.035 356,0.710,-0.064 357,0.697,-0.096

You are asked for a directory to save this file. Please use the default directory \RawData\_Files\Ellipsometry

Öffnen	? ×
Suchen in: Ellipsometry SiO2 on Si_100nm.xy SiO2 on Si_500nm.xy test4.xy	file is in nanometer
filename:     Si02 on Si_100nm.xy     open this file       pathname:     xy-file(*.xy)     cancel	350,0.846,-0.099         351,0.852,-0.099         352,0.858,-0.099         353,0.865,-0.099         354,0.871,-0.100         355,0.878,-0.101

# 7.1.6 **Print report**

This routine allows you to enter some user data (names of operator, of sample and so on), shows a preview and prints on the Windows standard printer. Changing the printer is possible only within Windows itself.

Entering of user data: you may also change the names of the labels (empty labels: this line is not shown on the final print). In the preview window you may zoom in and out. After pressing the print button you have the chance to change some printer options.

We recommend to buy the Option <u>NanoCalc-Online/Multipoint</u> for printouts of Multipoint Measurement, Result-Windows with Statistic Data's and Excel-Connection. If you want to get a printout of the complete screen or parts of it:.

# 7.1.7 Show Scout report

# 7.1.8 Exit

This routine exits ElliCalc and SCOUT and closes all windows. All important data have been written to the Thinfilm.ini -file before and will be reloaded in the next run.

#### Important warning:

Do NOT close SCOUT separately !!! This would break the OLE-connection between SCOUT and ElliCalc. The only way to restore this connection is to exit ElliCalc and restart the software !

#### 7.1.9 Function keys

If you click on the button F1, you get access to help functions.

# 7.2 Main menu "Screen"

7.2.1 Spectrometer data

	C	Mikrop	ack►
Spectrometer data (spectrometer define spectro master		×	The 4 displa They a Thinfil
coefficients	CCD auto	manual	single
enter password to change coefficients	Integration time (ms)		Chang
Intercept: 187.936	boxcar width (pixel)	9 -	syster protec
First Coefficient: .472416	samples to average		techni
Second Coefficient:0000138985	maximum intensity in spectrum (nm)	550.0 -	For ca chang
Third Coefficient: .000000000504			and or
channel activated			deviat
OK cancel F1=help		Hardware	

The 4 spectrometer coefficients are displayed for information purposes. They are automatically set by the Thinfilm.ini file which is specific for each single system.

Changing these values will screw up the system and is therefore password protected and only accessible for technical service.

For calibration purposes you may change these values (with a password and only within several percent deviation from your original values).

physical meaning:

These 4 numbers are the coefficients in a formula that shows the dependence between wavelength (in nanometers) and pixelnumber of your spectrometer according to the following formula:

$$\lambda = I + C_1 \cdot P + C_2 \cdot P^2 + C_3 \cdot P^3$$

with:

- I = intercept
- $C_1$  = first coefficient
- C<sub>2</sub> = second coefficient
- $C_3^{-}$  = third coefficient
- P = pixelnumber

Hint: Ask your hardware supplier if you have the impression that it might be necessary to recalibrate the spectrometer (a red HeNe-laser should show 632.8 nm)

# 7.2.1.1 Integration time

Whenever you change this value, it is written to disk (in file "Thinfilm.ini") and will be used as a startup value.

How to change integration time:

- 1. method = "auto intensity" button (or "init" button !): This method starts with the lowest available integration times for different positions of the polarizer and checks the resulting spectra (every 10 nm) to find an optimum integration time. The software will try to achieve a maximum signal of 75 % of the total range and will try to avoid saturation. The absolute value of the integration time will depend very much on the reflectivities of your reference materials, your substrate material and your layer material.
- 2. method = use the menu "options/spectrometer data" and and enter a value. Be careful: this may lead to bad results ...

You may check the value of integration time at any time without entering the menu OPTIONS: Put your mouse cursor over the button MEASURE and wait for about 2 seconds: a small window will pop up to inform you about integration time, samples to average and boxcar width. These values correspond to the <u>channel A</u> ("master spectrometer") if you use a double spectrometer.

#### 7.2.1.2 Boxcar width

physical meaning:



The Mikropack spectrometer is able to average over some pixels to increase signal/noise-ratio. A boxcar width of 1 pixel means no averaging at all (which is an ideal situation and would correspond to a very narrow fiber). This has to be used if you want to measure very thick layers (like 50 micrometers of resist)

A boxcar width of 5 pixels means an averaging over 2 pixels on the left side and 2 pixels on the right side (= 5 pixels altogether). This averaging routine is shifted from the left side of the simulated spectrum to the right side with a step size of 1 pixel only. Values of 5-9 are recommended if you want to measure films in the range of 1 micrometer or less as you get a better signal-to-noise ratio.

#### hint:

You may check boxcar width at any instance without entering the menu OPTIONS: Put your mouse cursor over the button REFERENCE or MEASURE and wait for about 2 seconds: a small window will pop up to inform you about integration time, samples to average and boxcar width. These values correspond to the **channel A** spectrometer if you use a double spectrometer.

#### 7.2.1.3 Samples to average

Whenever you change this value, it is written to disk (in file "Thinfilm.ini") and will be used as a startup value.

#### physical meaning:

The Ocean Optics / Mikropack spectrometer is able to average over some runs to increase signal/noiseratio.

#### Tips:

Try to use small values for Samples To Average while keeping the lamp intensity as high as possible (to get short measuring times). This is especially important in mapping mode.

You may check Samples To Average at any instance without entering the menu OPTIONS: Put your mouse cursor over the button MEASURE and wait for about 2 seconds: a small window will pop up to inform you about integration time, samples to average and boxcar width.

#### 7.2.1.4 Internal correct for dark

If you choose this option, dark current is corrected automatically (see Button measure).

The Ocean Optics / Mikropack Spectrometer is able to measure the dynamic dark current internally within a couple of pixels that are NOT irradiated by external light, and is correcting dynamically.

#### 7.2.1.5 Dark button

Buttons			×	
Change all units				
change	butt	ons		
start window		visible controls		
show startup image		show dark button		
_ analvze		show recipe button		
measure and analyze = 1 button		show mapping button		
factor for measurement integration time		waitbar is allowed		
		quality slider is allowed		

If you choose this option, dark current is corrected mathematically. This is only necessary if you can't protect your system against ambient light or stray light.



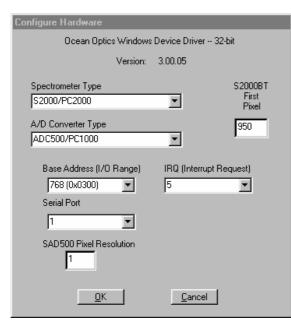
# 7.2.1.6 Maximum intensity

This value describes the maximum intensity in the spectrum of your (halogen ?) lamp.

This value helps ElliCalc to achieve an automatic adjustment of the integration time within the limits of the screen (=without saturation)

If you use a double spectrometer there are TWO such wavelengths corresponding to the different lamps and the different sensitivities of the two spectrometers.

If you use a double spectrometer with different sensitivity regions, e.g. 200-600 nm for channel A



("master spectrometer") and 500-1100 nm for channel B ("slave spectrometer"), ElliCalc joins the 2 spectra to get a single spectrum (200-1100 nm). The wavelength where the two overlapping spectra are joined is called "crossover wavelength". (any value is possible, 550 nm would be a good choice in this case).

To measure these sensitivities: just measure the spectrum of your (broadband)- light source with both spectrometers and you will easily see where the "best" wavelength is.

#### 7.2.1.7 Crossover wavelength

If you use a double spectrometer with different sensitivity regions, e.g. 200-600 nm for channel A ("master spectrometer") and 500-1100 nm for channel B ("slave spectrometer"), ElliCalc joins the 2 spectra to get a single spectrum (200-1100 nm). The wavelength where the two overlapping spectra are joined is called "crossover wavelength". (any value is possible, 550 nm would be a good choice in this

case).

To measure these sensitivities: just measure the spectrum of your (broadband)- light source with both spectrometers and you will easily see where the "best" wavelength is.

#### 7.2.2 Hardware settings

Please find these settings in Appendix A at the end of this handbook. (This window may look slightly different, depending on the latest version of the driver)

# 7.2.3 Limits

The spectrometer limits in magenta colors are showing the maximum range of your specific system.

🚟 Limits	X
define limits	
189 nm         spectrometer         1095 nm           ± 400.0         nm         ± 950.0         nm	4096 -
410.0 nm - data extraction limits - 2925.0 nm	
OK Cancel F1 = help	

#### 7.2.3.1 Plot limits

The plot limits are the left and right side of the plot on your screen and coincide with limits of measurement.

The adjustable values of the plot limits depend on the grating in your Ocean Optics / Mikropack Spectrometer and are noted in the calibration sheet of your system.

The plot limits may be changed within ElliCalc in steps of 1 nm.

1. normal mode to change the limits:

open the menu "spectrometer data \ limits" and enter numbers or use the up-down arrows



2. fast and rough method to change the limits:

If you click in the field near the LOWER numbers you may change the plot limits without entering the menu option/limits:

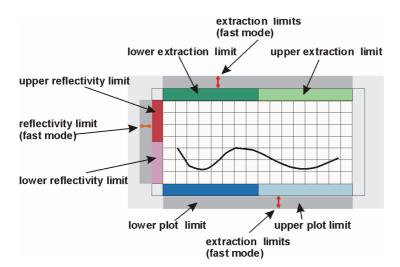
If you click in the **LEFT** half with your LEFT mouse button you will decrease the lower plot limit.

If you click in the **LEFT** half with your RIGHT mouse button you will increase the lower plot limit.

If you click in the **RIGHT** half with your LEFT mouse button you will decrease the lower plot limit. If you click in the **RIGHT** half with your RIGHT mouse button you will increase the lower plot limit. The same feature applies to plot limits and reflectivity limits.

3. fast and precise method to change the limits:

If you move your mouse very near to the lower part of the plot window (but still in the <u>grey</u> part) you will see a little vertical arrow and the value of the wavelength is displayed. If you now click with the left mouse button, you are able to change the lower plot limit (right mouse button=upper plot limit). The same applies to the other 2 grey zones = extraction and reflectivity limits (see picture)



4. Zoom You may zoom by dragging the mouse from one point to another within the plot area. If you click with the right mouse button a small popup window will appear with the chance to undo this zoom. You can also change the plot limits back to the full range (according to your spectrometer limitations). You can also set the current plot limits as a standard or return to a previously set standard.

# ATTENTION:

to be consistent with data handling, ALL materials files contain n and k data between 150 nm and 1100 nm. Usually only *parts* of these data are measured data (e.g. between 206 nm and 840 nm or between 300 nm and 1100 nm). If you simulate, the valid part of the curve is shown in *black* while the rest is shown in *grey* (and you get a message).

Extraction limits are restricted to the range of valid n and k data.

# 7.2.3.2 Extraction limits

These limits cannot be larger than the plot limits. Try to use a large extraction range as long as your signal is "good".

- 1. normal mode to change the limits: open the menu "spectrometer data \ limits" and enter numbers or use the up-down arrows
- 2. fast and rough method to change the limits:

If you click in the field near the UPPER numbers you may change the extraction limits without entering the menu "spectrometer data \ limits".

If you click in the **LEFT** half with your LEFT mouse button you will decrease the lower extraction limit.

If you click in the **LEFT** half with your RIGHT mouse button you will decrease the lower extraction limit.

If you click in the **<u>RIGHT</u>** half with your LEFT mouse button you will decrease the lower extraction limit.

If you click in the **<u>RIGHT</u>** half with your RIGHT mouse button you will decrease the lower extraction limit.

The same feature applies to plot limits and reflectivity limits.



3. Fast and precise method to change the limits:

If you move your mouse very near to the upper part of the plot window (but still in the grey part) you will see a little vertical arrow and the value of the wavelength is displayed. If you now click with the left mouse button, you are able to change the lower extraction limit (right mouse button=upper extraction limit)

#### ATTENTION:

to be consistent with data handling, ALL materials files contain n and k data between 150 nm and 1100 nm. Usually only *parts* of these data are measured data (e.g. between 206 nm and 840 nm or between 300 nm and 1100 nm).

If you simulate, the valid part of the curve is shown in *black* while the rest is shown in grey (and you get a message).

Extraction limits are restricted to the range of valid n and k data.

#### 7.2.3.3 Y limits

To zoom in the plot and to see some more details you may change the Y limits. In most cases you will not need this option.

- 1. normal mode to change the limits: open the menu "spectrometer data \ limits" and enter numbers or use the up-down arrows
- 2. fast and rough method to change the limits:

If you click in the field near the LEFT numbers you may change the reflectivity limits without entering the menu option \ limits:

If you click in the <u>LOWER</u> half with your LEFT mouse button you will decrease the lower reflectivity limit.

If you click in the <u>LOWER</u> half with your RIGHT mouse button you will decrease the lower reflectivity limit.

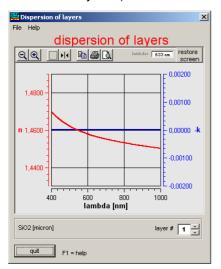
If you click in the <u>UPPER</u> half with your LEFT mouse button you will decrease the lower reflectivity limit.

If you click in the <u>UPPER</u> half with your RIGHT mouse button you will decrease the lower reflectivity limit.

The same feature applies to plot limits and reflectivity limits.

2. Fast and precise method to change the limits:

If you move your mouse very near to the left part of the plot window (but still in the grey area) you will see a little horizontal arrow and the value of the wavelength is displayed. If you now click with the left mouse button, you are able to change the lower reflectivity limit (right mouse button=upper reflectivity limit)



#### 7.2.4 Dispersion

This form shows the refraction index n and the absorption index k (within the plot limits) for different layers. This form is just a tool to control your data, nothing can be really changed in this form.

There are two cursors available for n and k (press the cursor symbol and drag them with the mouse, atrthe beginning they are on top of oneanother)

#### ATTENTION:

To be consistent with data handling, ALL materials files contain n and k data between 150 nm and 1100 nm. Usually only *parts* of these data are measured data (e.g. between 206 nm and 842

nm or between 300 nm and 1100 nm).

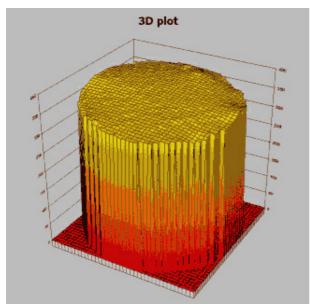


If you simulate, the valid part of the curve is shown in *black* while the rest is shown in grey (and you get a message).

Extraction limits are restricted to the range of valid n and k data.

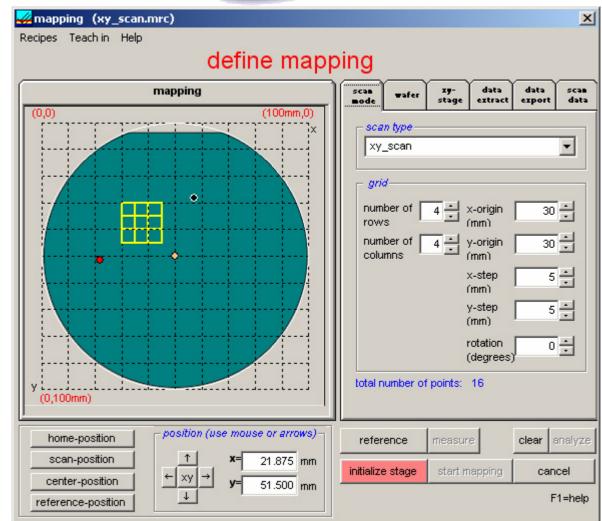
# 7.3 Main menu "Externals"

# 7.3.1 Mapping



You need a mapping-xy-stage and a special mapping add-on software for ElliCalc to measure in mapping mode. In this mode it is possible to measure and display your film parameters as a function of x and y.





#### main menus of mapping mode

1. Menu "Recipes"

- Save as map recipe
- Load map recipe

Here you may save or load ALL the settings you have done in all the various possibilities. It is recommended to save your usual settings in a recipe. It is possible to use a special recipe name like "myownRecipe". Recipes for mapping will receive the extension ".mrc" and will be saved in menu "Recipes\Map\_Recipes"

#### 2. Menu "Teach in"

This will be explained later in the following section

#### 3.menu "help"

this is the usual access to help functions

#### main buttons (lower right side)

#### init

you can initialize your ellipsometer (right mouse button=time adjustments possible) **auto intensity** 

you can adjust the nintegration times automatically (right mouse button=time adjustments possible) **measure** 

you can take a real (test) measurement with your sample. Thus you can control all settings before you start the mapping



#### clear

clears the screen

#### analyze

you can analyze the layer parameters your sample. Thus you can control all settings before you start the mapping

#### initialize stage:

After starting mapping mode you have to initialize the xy-mapping stage first.

Until the xy-mapping stage is initialized the function start mapping is deactivated.

#### start mapping

this will start the mapping sequence

cancel

leave mapping mode

scan mode	wafer	19- stage	data extract	data export	scan data
×y,	<i>n type</i> — _scan				•
row	ber of		×-origin (mm) y-origin		
	mns		rmm) κ-step mm)	·	
		i I	y-step (mm) rotation	0	
total r	umber of		(degrees) 16	r	

#### Scan mode: a. shape of the wafers:

1. You may use square or round wafers.

2. To use your own design as a background you need to edit the file OwnDesign.bmp within the ElliCalc directory (this is possible with lots of drawing programs, or ask your software supplier for help).

#### b. wafer size

Wafer size may be changed between 50 mm and 300 mm (= 8"). A grid is shown with a constant grid distance (e.g. 10 mm).

#### c. scan region

It is possible to change:

- the x and y coordinates of the origin in steps of 0.1 mm
- the number of rows and the number of columns of the scanning grid
  - (from 1 to 100)
- the size of the x and y steps (in multiples of 0.1 mm)

The wafer plot shows what you are doing.

#### d. rotation

here you can rotate the scan region



# e. mapping positions

#### measuring position:

If you press one of the position buttons, the mapping stage will immediately go to this point and a red circle is displayed on the screen. Additionally the coordinates of this point are displayed. If option "measure on each click" in Tab2 is activated, a measurement will be performed.

You may reach any point by clicking with the LEFT mouse button or by entering the coordinates and pressing the xy-button.

You may move up and down or left and right by pressing the appropriate arrow buttons. If you press the arrow buttons with the left mouse button the cursor will move in increments of xSteps. If you press the arrow buttons with the right mouse button the cursor will move in smaller increments of xSteps/10

#### f. position buttons:

1. home position

Typically this is in the right lower corner of the xy-stage. The hardware of the stage will define this point at the beginning of the mapping experiment (and it can be changed manually in the ini-File in section [mapping], HomepositionX/Y=.... The numbers mean the percentage compared to wafersize (0.05 = 5% of wafersize)

2. scan position

this is the origin of the scanning coordinate system

3. center position

this is the center of the (round) wafer stage

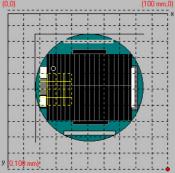
The wafer plot shows what you are doing.

scan mode	wafer	19- stage	data extract	data export	scan data	] ]
circ squ		ostrate —			0 0	
flat	er shape t_top				•	
	e of subs ier size	trate —	1	00 mm	•	

#### Wafer:

The shape of the substrate may be:

- a. circular (between 50 and 300mm)
- b. square (between 50 and 300 mm)
- c. your own design (change file "OwnDesign.bmp" with any drawing software)
   example:



Wafer size may be changed between 50 mm (= 2") and 300 mm (=8"").



scan mode waf	er II- stage	dətə extract	data export	scan data							
_×y referenc	e position-	wait in	terval —								
xReference 46.38 wait interval after positioning:											
yReference • 16.75 60 millisec											
-xy center position scanmode											
xCenter o 50.0 (mm)											
yCenter o 50.0 (mm)											
radius ( (mm)	3.00										
	scan wafer zy- mode wafer stage extract export data										
node visibility	during ma	extract	export	data							
node visibility	er stage	extract	export 3D plot 2D plot	data							
ware visibility	during ma	p	export 3D plot	dətə							
visibility	er stage r during ma ness	p	export 3D plot 2D plot	dətə							
visibility d1 fitt plot simu plot thick	er stage and during ma ness	p	export 3D plot 2D plot	dətə							
visibility d1 fitt plot simu plot simu plot thick	if stage (during ma ness allated curve (ness value og options- thickness o	p	3D plot 2D plot 1D plot	dətə							
■ode visibility d1 fitt visibility d1 fitt v u plot simu plot simu plot thick analyzin analyze retry if b	during ma ness ulated curve cness value	p	3D plot 2D plot 1D plot	dətə							
■ode visibility d1 fitt visibility d1 fitt v u plot simu plot simu plot thick analyzin analyze retry if b	if stage (during ma ness ulated curve (ness value (ness value (ness value (ness value (ness value) (ness valu	p	3D plot 2D plot 1D plot	data							

#### Stage:

Ocean Optics / Mikropack can deliver an xy-stage for 8" (=300mm).

#### a. serial port:

The port is used for communication with the mapping-stage. Ask your hardware supplier for details.

To drive the mapping-stage you need one COM-port for xy-stages (or a USB port and a converter).

#### b. wait interval:

after each measurement the scanning may be interrupted for a certain interval of time

#### c. single step:

If you activate this option each single measurement is waiting for a trigger signal (a keystroke with ENTER key or an external TTL trigger signal which is applied to the spectrometer. Ask your hardware supplier...)

# Data extract:

#### a. plot during map

With this option you choose the layer you want to "extract" = to display.

You cannot choose more than <u>one</u> parameter as only one parameter can be displayed at a time. If you use ElliCalc\_10nk you may calculate up to 10 layers (but display ONE of these)

#### b. analyzing options

analyze parameters on each left mouse click. This is a very useful feature to make a quick check on film parameter distributions on your wafer (do not forget to activate option "plot value during mapping").

fitness limit: if your results are completely wrong for some reasons, all measured values with a fitness greater than this fitness limit here will be set to zero. This feature is useful, if dust causes a measurement error during mapping. Without this feature you might get enormous spikes.

#### c. visible during map

You have the choice between 1D-plots for line scans, 2D-plots and/or 3D-plots.

The 2D-plot and the 3D-plot contain the same data. A 1D-plot is possible only if you measure along ONE row or column (and not a two-dimensional field.)

#### d. number of runs

You have the choice between a single run (for real measurement purposes) and a nearly infinite number of runs (=30000) for demonstration purposes.



scan mode	wafer	xy- stage	dətə extract	data export	scan data
⊢ afte	r map —				
nam	e of map	file			
			C: timp	oʻtest.ma	p
	rt comme -and Exc	el file S	yfirsttest canMode ayer(s) 1		-
sho	w results	s windov	V		

#### Data export:

You may choose the following options during a mapping experiment:

- 1. plot the simulated curve
- 2. plot parameter value

It is more informative to see the analyzed curve and the calculated parameter value during the simulation, but this is time-consuming. If the mapping takes a longer time it is recommended to switch off these 2 features.

You may choose the following options after a mapping experiment:

- 1. write data as map-file
- 2. insert comments in map or Excel-files
- 3. show results window

#### 1. Write data as map-file

All parameter and fitness data together with some coordinate information are written to a ASCII-file in directory "ElliCalc\data\map files".

examples can be found in the directory "ElliCalc\data\map\_files" 2. insert comments in map or Excel-files

you may enter text like "sample #1, "Paul McCartney" or "myfirsttest".

This text will be a header for your map-files and also for all exported Excel\_files

#### 3. show result window

If you accept this option a results window with possibility for Excel export will open after the mapping process.

scan mode	-	afer	19- stage	da exti	lta ract	data export	scan data
	ker	data					
no		0	marker1	0	ma	rker2 🔿	
mark	(er	ж=		20	Γ	80	
		y=	· ·	40		60	
		x		V			T
	1		30.00			30.000	
	2		35.00	00		30.000	
	3		40.00	00		30.000	
	4		40.00	00		35.000	
	-5		35.00	00		35.000	
	6		30.00	00		35.000	
	- 7		30.00	00		40.000	
	8		35.00	00		40.000	
acc	ept 1	teach	n-in		test	single sta	eps
	_	_		_	_		

# Scan data:

This feature is used in microscope arrangement (e.g. for measuring structured wafers) if you want to hit the xy-positions with higher accuracy.

Usually the wafer or sample will be positioned on the chuck with some mechanical adjustments (like pins on 2 sides of the wafer and adjustment to the wafer flat). This will result in a medium accuracy, but not comparable to fine positioning like in semiconductor photolithography.

How to get a higher accuracy:

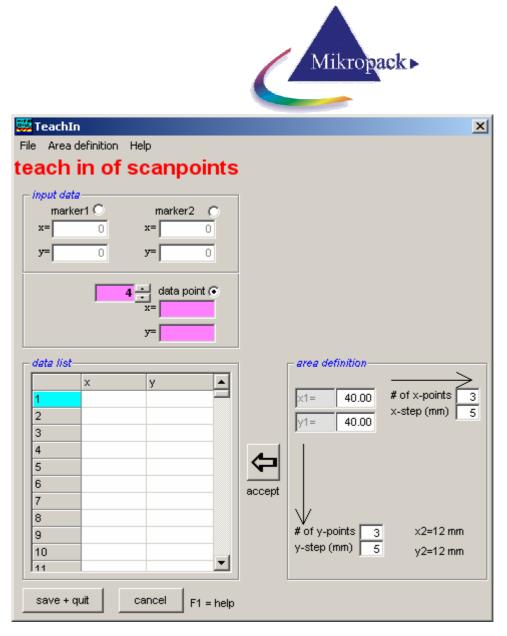
1. click on "marker 1":

The stage will move to this position. If you now look through the microscope you will see a slight deviation between the illuminated spot and the real marker on your wafer.

- 2. Correct this deviation by moving the stage (use the keyboard arrows: clicking or pressing once = 10 micrometer, SHIFT + clicking or pressing once = 1 millimeter). The red circle on the screen will move slightly off the marker.
- 3. Repeat step 1 and 2 for marker 2
- 4. Now the software knows both deviations and is able to calculate what to do: shifting the origin and rotating the scan pattern a little bit. Press the button: "accept teach-in"
- 5. Control the values of rotation angle and xy-origin
- 6. Start mapping as usual

#### Teach in:

Teach in is an interactive tool to write new map-recipes without using text editors to edit the map recipe file.



Now the method with teach-in-mode:

- 1. open the mapping window (main menu "map data") and then the menu "TeachIn"
- 2. you will see this window:
- 3. to set the first marker position, click on "marker 1", then move the measuring position with the arrow keys on the keyboard
  - or by clicking somewhere in the wafer area
  - or by typing values in the text box
- 4. to set the second marker position, click on "marker 2", then move the measuring position as before
- 5. to set the first data point, click on "data", then move the measuring position as before
- 6. to set the next data point, click on the up down counter (now it should show the value 2 instead of 1) and then move to the measuring position as before
- 7.save the new recipe (like test.mrc) with the extension .mrc

It is possible to change any or these values by clicking on the first columns in the appropriate row. Then the stage moves to that position and you are able to change it.

It is NOT possible to interchange or delete rows.

# 7.3.2 Result List

As soon as the mapping is finished you will see a result list:

		· · · · ·	mappi	ng res	uns		
fitness	<u> </u>	d1 )					
	1	2	3	4	5	6	7
	123.0	123.0	124.0				
!	124.0	124.9	124.0				
	123.1	123.0	123.9				
0							
1							
2							
3							
4							
Ū į							•
nean valu	3 = 1	23.66 σ=	. 0.6	67 maximum	value =	124.90 fitne	ess limit 20.000
			-				ss innit [ 20.000
no of failur	res	0 3σ=	2.0	02 minimum	/alue =	123.00	
close all windows	F1 =	help	Ň	write data as EXCEL-file	show data as 1D-plot	show da as 2D-pl	

On the first page you see the measured thickness values for each layer. In the picture above there was just one layer and  $3 \times 3 = 9$  measured data points. In the last page you can see the associated fitness values for each coordinate. In the text windows below the data window you see mean values, maximum and minimum values and standard deviation  $\sigma$ , the  $3\sigma$ -value and the number of failures (according to the measured fitness and your fitness limit).

If you did not choose a regular scan pattern, you will see a one-dimensional list.

If you click on the buttons with the numbers in a row or a column you will <u>highlight</u> a certain number of data points (in the picture above column 3 was highlighted). Now you can control these selected values in a one- or two-dimensional plot by pressing the appropriate button in the last row. You may also choose a smaller amount of data by dragging with the mouse (e.g.  $2 \times 2 = 4$  points).

If you press "write data to EXCEL-file" EXCEL will be opened (if installed on your PC) and the data will be transferred to a spreadsheet.

With "close all windows" you will return to NanoCalc main window and all mapping windows will be closed.

If you enter a value for "fitness limit" and press ENTER, the screen will be updated and all cells with a higher fitness than your limit will beplotted in red (cells in grey show that this point was outside the wafer).

# 7.3.3 Analyze mapped data

This feature helps to analyze mapped data that have been measured earlier.



You are asked for a file name (extension .map) in directory ElliCalc\data\map\_files. Then the results window is opened and you may inspect your data, plot the data or export them to Microsoft Excel.

# 7.3.4 Structure of .map-file

The first 2 lines are comments, the file format is very strict.

test4 user4 \*\*\* xy-ScanMode 1 Layer(s)

1 Layer(s)ToExtract

2 Row(s)

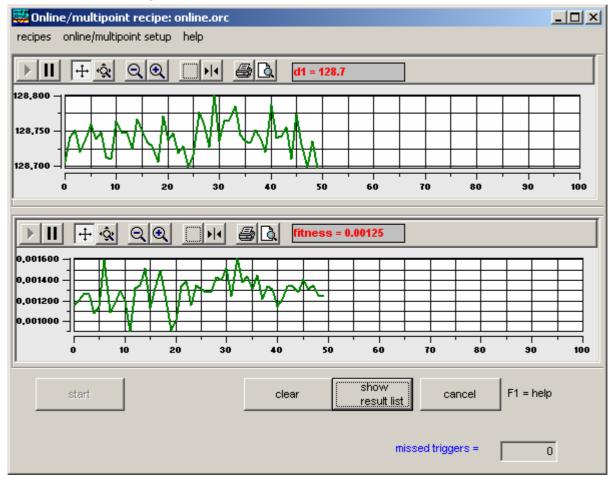
2 Col(s)

4 total points

5 xStep 5 yStep

IndexNo, row, col, x, y, fitness, d1 1, 1, 1, 30.000, 30.000, 0.048, 132.880717 2, 1, 2, 35.000, 30.000, 0.048, 132.806642 3, 2, 1, 35.000, 35.000, 0.048, 132.918102 4, 2, 2, 30.000, 35.000, 0.048, 132.858514

#### 7.3.5 Online/multipoint measurements





#### Load online recipe:

The online setup window contains lots of input data, so usually you will want to use an online recipe to do that job for you.

You will be asked for a file name (usually in directory "ElliCalc\recipes\online\_recipes"). After loading this file nothing happens except new parameters in setup, like different y-axis or other trigger parameters.

Online/multipoint recipe: online.orc												
onlin	e/mu	ltipoin	it seti	Jp H	elp							
nline/	multi	point	recipe	•			_					
as onl	ine/m	ultipa	int re	cipe			ł					
	_						L					
							F					
	onlin nline/	online/mu nline/multip	online/multipoin nline/multipoint	online/multipoint setu nline/multipoint recipe	online/multipoint setup h nline/multipoint recipe	online/multipoint setup help	online/multipoint setup help					

#### save as online/multipoint recipe:

The online setup window contains lots of input data, so usually you will want to use an online recipe to do that job for you.

If you changed some setup parameters you can save them as a new online recipe. You will be asked for a new file name (usually in directory "ElliCalc\recipes\online recipes").

#### online/multipoint setup:

Depending on the switch "show setup first" in menu "online\setup" the setup window for online measurements is shown at first or not. If you want to rename your files at the beginning of each measurement cycle it is recommended to open the setup window first.

The setup window contains lots of input data, so usually you will want to use an online recipe to do that job for you.

🗱 Online/multipoint setup		×
online/m	ultipoint	t setup
save mode tr	igger mode	plot mode
save mode	write_to_file_im	terval
no save C	write file every	5 values
continous save to RAM C continous save to disk •	= every	133.333 min
filenames       default name:       demo       add date to name       add time to name	comment	
add # to name	= help	

# Save mode:

In this first part of online setup you can choose:

#### a. Option "save mode"

- 1. do not save the online data
- all data are lost and only visible on screen 2. save online data to RAM
- at the end of the run you may observe and analyze your data in the results window

3. save online data to disk according to option "write\_to\_file\_interval" all data are written to file in smaller portions with filenames that are determined in option "filenames"

#### b. Option "filenames"

- 1. choose a name like "series 1" or "test4" or alike
- 2. choose one or more options "add....." example: a filename might look like: test156.onl

#### c. Option "trigger interval"

You might want to save the value (not the file !) every trigger, but for some reasons you might want to save only every third trigger.

#### d. Option "write to file interval"

You might want to save the file (not the value !) every trigger, but for some reasons you might want to save only



×

every third trigger.

#### Trigger:

In this second part of online setup you can choose:

#### a. option "trigger mode"

you can trigger continuously by adjusting the appropriate software parameters like trigger interval.

you can trigger externally with a TTLsignal to your spectrometer. Please consult your hardware supplier...

# b. option "trigger interval"

Here you choose the time interval between two software triggers. Pay attention on the correct unit

# c. option "number of runs"

You might want to run a certain number of data points only or (nearly) infinitely. Attention: "infinite" means about 999999 data points.

save mode     trigger mode     plot mode       trigger interval     min     C       trigger every     1600     sec     C       test recommended time     msec     C       # of runs     # of runs     Frigger modes	online	/multipoi	nt setup
trigger every 1600 sec msec test recommended time msec	save mode	trigger mode	plot mode
	trigger every 1600	min O co sec O ke ime ex	ontinously   ypress (ENTER)
no of runs     6     C infinite no of runs     ok     cancel     F1 = help	no of runs     infinite no of runs	s	

🐺 Online/multipoint setup

🧱 Online/mu	ltipoin	t setu	p					X				
online/multipoint setup												
save mode trigger mode plot mode												
select online/multipoint parameters :												
auto min value max value d1 fitness												
chart	1		0	1100								
chart	2											
chart	3		0.0000	0.1000		✓						
chart	4											
							►					
hints: — use up to 4 charts — use as few parameters as possible												
ok	C8	ancel	F1 =	help								



					luitipt	<u>Jint mode</u>				
Resu	lts									
File	Help									
						Online I	results			
	fitnes:	~	$\gamma^{}$	d1	$\sim$					
	nanoos	•	-							
1			128.3							
2			128.1							
3			128.1							
4			128.3							
5			128.2							
6			128.2							
7			128.2							
8			128.2							
9			128.3							_
10			127.8							
11			126.6							
12			126.9							
13			128.2							
14			10.0							
15			10.0							-
_										
me	ean valu	ie =	1	04.44	σ=	49.589	maximum value =	169.70	fitness lir	nit 10.000
no	) of failu	ires		0	3σ=	148.767	minimum value =	10.00	r i i i i i i i i i i i i i i i i i i i	
					50-	140.707		1 10.00		
(	close all	- 1				wri	te data as 🛛 🗍 show	vidata sho	ovv data	show data
V	vindow:	s	F1 =	help		E	XCEL-file as 1	D-plot as	2D-plot	as 3D-plot
					con	nments: test1	*****			
retu	irn to on	nline				100t1				 _
										<u>▼</u>

On the first page you see the measured thickness values for each layer. In the picture above there 5 measured data points. In the last page you can see the associated fitness values for each measurement. In the text windows below the data window you see mean values, maximum and minimum values and standard deviation  $\sigma$ , the  $3\sigma$ -value and the number of failures (according to the measured fitness and your fitness limit).

You may choose a smaller amount of data by dragging with the mouse (in the picture above: 3 points). If you press "write data to EXCEL-file" a .xls-filen is written (even if Excel is not installed on your PC !). With "close all windows" you will return to ElliCalc main window and all mapping windows will be closed.

# 7.3.6 Analyze online/multipoint data

Deput list for online/multipoint mod

This feature helps to analyze online/ multipoint data that have been measured earlier.

You are asked for a file name (extension: .onl) in directory ElliCalc\data\online\_files. Then the results window is opened and you may inspect your data, plot the data or export them to Microsoft Excel.

# 7.3.7 Structure of .onl-file

The first line is a comment, the file format is very strict.

```
test1
***
55 total points
***
triggercounter, time, fitness, d1
1, 10:35:19, 0.010, 128.3
2, 10:35:19, 0.010, 128.1
3, 10:35:20, 0.014, 128.1
```



- 4, 10:35:20, 0.009, 128.3
- 5, 10:35:21, 0.008, 128.2

# 7.3.8 RS232

Within the RS232 menu you may send data via two virtual serial ports to the Faulhaber motors (used for xy-stages etc)

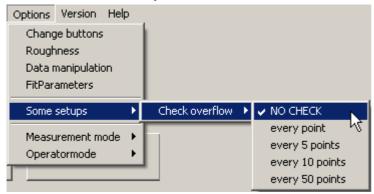
<b>5232</b>	×		
Hardware			
serial RS232 port			
list of commands en v0 ver v500	mapping motors         ellipsometer motors           x-axis         Image: second		
sor0 v-500 la+1000 (+m) lr+1000 (+m) la-1000 (+m) lr-1000 (+m)	messages       send string       received string		
analyzer / polarizer positions       analyzer $A = -45.0^{\circ}$ $P = 90.0^{\circ}$			
	quit F1 = help		

You may open and close each virtual port separately. If you send the signal "ver" the motors of the xystage should answer (more precise: this command is "1ver" for motor1 and "2ver" for motor2). Ask your hardware supplier for the motor numbers.

# 7.3.9 Vision system

If you own a vision system with an IDS uEye-camera you may turn on the camera with this menu

# 7.4 Main menu "Options"



# 7.4.1 Change buttons

In this window you can make visible or invisible:

- The startup image:

If you want to start ElliCalc with a nice picture: activate this option !



- The picture will disappear after some seconds or you might "click it away"
- a measure and analyze-button:
- to combine the functions to the measure and the analyze button
- a dark button:
- to measure any dark current separately
- a mapping button:
- to make it easier to use mapping
- a load recipe button:
- to make it easier to load recipes
- show SCOUT window:

it is not necessary to see the SCOUT window inside ElliCalc, but for experienced users this might be helpful

🐺 Buttons		×	
change buttons			
start window         show startup image         analyze         measure and analyze = 1 button         factor for measurement integration time         ok         cancel       F1 = help	visible controls show dark button show recipe button show mapping button quality slider is allowed		

# 7.4.2 Some setups

# 7.4.2.1 ElliCalc setups

Here you can change:

• the number of polarizer steps

Typically ElliCalc uses 18 steps per revolution of the polarizer = a measurement every 20°. This is good for most purposes. If you use less steps (e.g. only 9 steps) you might loose presicion (but you may try, it's faster...)

• a dark offset Normally this value is zero.

# 7.4.3 User mode

In user mode certain restrictions apply: e.g. the user is not allowed to use certain menus or certain buttons.

The default password to come back to administrator mode is: "admin". This password can be changed arbitrarily, there are no severe restrictions concerning passwords. Please use letters and numbers only.

# 7.4.4 Operator mode

In administrator mode no restrictions apply. This mode is reserved for the administrator of the system.

The administrator may define the options that will work for a standard user. To get this Rights of User - window just click on "administrator mode".



### 7.4.5 Change colours

In this menu you may change the colours of your layers in the layer stack. It is just an optical effect and has nothing to do with calculations.

Click on a layer number and then on a colour.

### 7.4.6 Remote control

There is a very powerful **OLE** remote control as well. Ask your software supplier...

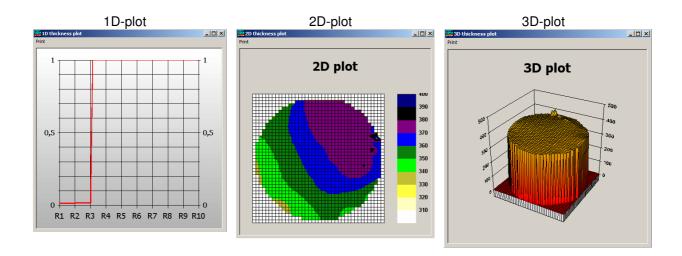
### 7.5 Main menu "Version"

This menu is visible only if you own a "combiversion" = a combined version of NanoCalc and ElliCalc. You may switch to the other application

### 7.6 Chart and chartdesigner

Chart Designer Chart Title Footnote Legend Plot X Axis Y Axis Second Y Axis Series Series Series Series Labels	Type Backdrop Picture Chart C 2D O 3D Line (Tape) Area Step Combination Horizontal Bar Clustered Bar Pie Doughnut Gantt	Reset Chart To Defaults Layout Text For Printing For Display Data in Rows		f you produced a ID-plot or 2Dplot or 3D-plot you may change nearly ALL parameters of the plot by clicking with he RIGHT mouse putton Hint: To change the view position : keep CTRL
	Gantt Surface	rechen Ü <u>b</u> ernehmen Hilfe	b tł	bosition : keep CTRL button pressed and nove the mouse at he same time. For further

information see VCFI5.hlp in the help directory of your ElliCalc installation.



During mapping it is possible to produce 1D-plots, 2D-plots and 3D-plots.



These plot types can be changed interactively after the mapping was finished. Click with <u>right</u> mouse button on the plot to get access to the "chart designer".



# 8 Special features for "SCOUT mode"

### 8.1 Main menu "File"

### 8.1.1 Change layer recipe

if you load a (.lrc)-recipe containing a link to a SCOUT .sc2-recipe and measure your sample, SCOUT will analyze in the background and the results will be displayed in the graphical user interface of Elli-Calc.

The layer stack and all layer parameters are defined within SCOUT and are extracted by SCOUT. Elli-Calc is only a user interface. There are lots of data in ElliCalc's internal .lrc-recipe, but most of them are not important in this context: SCOUT is the "master".

With "change layer recipe" you may change some of the layer and fit parameters of SCOUT (but not all). Your changes are NOT permanently saved to the SCOUT recipe on the harddisk, only to the running SCOUT instance. If you are convinced that your changes are good enough you may also save them permanently (at the moment only via Scout itself).

To switch to a completely <u>new</u> recipe you have to load another .lrc-recipe with a different SCOUT .sc2recipe (do NOT use SCOUT directly !). With "change layer recipe" it is not possible to change the layer structure, only values of the recipe.

<mark>4 SCOUT</mark> File	fit parameters						×				
	SCOUT fit parameters										
layer	SCOUT parameter	min	value	max	range	method					
	Angle of incidence	68	70	72	user	frozen					
1	Layer thickness	10	1.788E+02	1.000E+03	user	gridfit100					
							-				
save to SC	OUT cancel	F1 = help									

SCOUT fit parameters	Changing	a value
----------------------	----------	---------

ile											
SCOUT fit parameters											
layer	SCOUT parameter	min	value	max	range	method					
	Angle of incidence	68	70	72	user	frozen					
1	Layer thickness	5.364E+01	1.788E+02	5.96E+02	wide 💌	gridfit100	-				
					narrow						
					wide user						
					unlimited						

SCOUT fit parameters: Changing a range for parameters



🚜 SCOUT (	it parameters						×
File							
		SCOUT	fit parame	eters			
layer	SCOUT parameter	min	value	max	range	method	
	Angle of incidence	68	70	72	user	frozen	
1	Layer thickness	5.364E+01	1.788E+02	5.96E+02	user	gridfit100	
						Simplex frozen gridfit10 gridfit20 gridfit50 gridfit100	T
save to SC(	DUT cancel	F1 = help					

SCOUT fit parameters: Changing an extraction method

### 8.2 Main menu "Screen"

### 8.2.1 Psi/Delta or tan(Psi)/cos(Delta)

Her you may switch between a display in Psi/Delta or in tan(Psi)/cos(Delta), whichever you prefer. The data transfer to SCOUT (via a file EC\_data.xy in Internal\_Files) is done in tan(Psi)/cos(Delta)

### 8.3 Main menu "Options"

### 8.3.1 Fit parameters

🙀 Fit parameters 🔀	🐺 Fit parameters 🛛 🔀
Help <b>change fit parameters</b> General Traffic Lights	Help change fit parameters General Traffic Lights
time for simulation in sec exact <	Traffic lights
OK reset to standard F1 = help	OK cancel reset to standard F1 = help

In the 1st Tab "General" you may change the time for simulation = the number of Simplex fits. A longer time usually means more precise data (up to some limit...)

In the 2nd Tab "Traffic lights" you may change the fitness values for the trafficlight = good/medium/bad



### 8.3.2 Some setups

Here you can change:

- 1. the number of the motor steps. At the moment 18 motor steps = 20 °/step are strongly recommended
- 2. Scout stoptime in seconds. This is equivalent to the above mentioned slider in menu "Fit parameters" / Tab1
- 3. Change colors. Here you may change the colors of the layers. First click on the layer area on the left side. Then move the mouse over the large coloured area and click if the colour pleases you. Then press OK

<mark>4</mark> Layer co	lors	×	1
e	dit laye	r colors	
layer9	-	n a layer to select it	
layer8	and t	hen click here	
layer7			
layer6			
layer5			
layer4			
layer3			
layer2			
layer1	I		
layer0	F1 = help	accept	
ok	cancel	reset	



## 9 Special features for "internal mode"

This internal mode can only extract <u>thicknesses</u> in layer stacks, so this is much more restricted than "SCOUT mode". You do not need the SCOUT software and it may be faster than SCOUT in simple cases.

To reach this mode you have to use a lrc-recipe without an internal link to a SCOUT .sc2-recipe. There are different possibilities to do do this:

- Press SHIFT+CTRL+F12
- Or: load a special .lrc-recipe, called "no\_recipe.lrc"
- Or: edit any .lrc-recipe manually: just remove the name of the .sc2-recipe after "Scout\_FileName\_EC=name.sc2" in section [Scout]. Be careful with this manual editing, make a safety copy! Finaly the line should read: "Scout\_FileName\_EC="

After this change, you will see a new button "Edit Structure", which allows you to edit your own layer stack.

Measure	to I	neasure	1	Clear							Calculatio
	ious: OF		1		_	_	_	_	_		
cc <sub>1.10</sub> elta)	450.0nm	500.0nm	550.0nm	600.0nm	650.0nm	700.0nm	750.0nm	800.0nm	850.0nm	900.0nm	950.0nm
0.96											
0.65											
0.41	_					_	_				
0.14											
-0.1	_		_			_		_		_	
-0.2						_					
-0.5											
-0.8	—			_		_	_				
-1.10	450.0nm	500.0nm	550.0nm	600.0nm	650.0nm	700.0nm	750.0	<u>e00</u> .0nm	850.0nm	900.0nm	950.0nm
, Simulati	on							A		70.0	🖌 Setu
o minanai.	1										
simulate							e	siit 🛛 📕	C2_(the	rm) 🖳	1.4571
	-						stru	cture			
								\$i	(00)		JB- 3.8714
								<u> </u>	//////		
								Air			

### 9.1 Edit structure button

You will see this button and this window only <u>if you do not use a SCOUT recipe</u> = if you use ElliCalc's internal mode. You get good results, but only for the extraction of thicknesses (not dispersion) In this menu "edit layer structure" you have to define your own layer structure



### 9.1.1 General

🐺 E	dit layer structure					×				
File	Help									
	edit layer structure									
L6	others 💌	n2_2 💌		80.0 🗧 100.0 🛨	140.0 🔹	narrow 💌 🔺				
L5	others 💌	n1_4 💌		80.0 🕂 100.0 🕂	140.0	wide 💌				
L4	nitrides 🗾 👻	SiN		80.0 🕂 100.0 🕂	140.0	wide 💌				
L3	semiconductors 📃 💌	Si_poly_50		80.0 🕂 100.0 🕂	140.0	narrow 💌				
L2	others 🗾 💌	Cauchy		80.0 🕂 100.0 🕂	140.0	narrow 💌				
L1	oxides 🗾 👻	SiO2_(therm)		0.0 🛨 500.0 🕂	1500.0	narrow 💌				
LO	semiconductors 🗾 💌	Si(100)	·			Ţ				
Air	catalogue	material	d Rnkf	estimated <b>estimated</b> lowerlimit <b>value</b>	estimated upper limit	limits mode				
	number of layers: 6									
	OK cancel									

In the menu Edit Structure you may enter:

- 1. The type of catalogue like:
  - oxides nitrides semiconductors
- 2. The type of material within one specified catalogue, like "oxides":
  - SiO<sub>2</sub> CuO TiO<sub>2</sub>
- 3. The number of layers (in the present version: 1 to10)
- 4. The thickness of all layers in nanometers. This value is regarded as an EXACT value for simulations and as a GUESS for analyzing measured spectra. Whether this guess is used (or not) will depend on the measurement mode.
- 5. A lower and an upper limit of the thickness. These values are NOT used in simulations. Whether these limits are used for measuring purposes (or not) will depend on the measurement mode.
- 6. An option "fixed":

If you press this option, the lower and upper limits are fixed to the value of the thickness of the layer. Such a layer is regarded as "well known".Of course it does not make sense to use three fixed layers, there is nothing left to analyze.

7. An option "narrow limits"

If you press this option the lower and higher limits are set to about 80-100 nm below and above the value of the thickness. This is equivalent to having a FAIRLY GOOD KNOWLEDGE of the thickness

8. An option "wide limits"

If you press this option the lower and upper limits are set to a wider range. This range depends on the settings of the menu EditStructureSetup and may be set to:

- -- well defined values like: lower limit=200 nm and upper limit=800 nm
- (with any thickness value between 200 and 800 nm)

-- constant range like lower limit=thickness-100 nm and upper limit=thickness+100 nm

Thus the search region is restricted to a rather wide, but more or less "reasonable" range. Of



course you may also set the limits very narrow, even to a search range of zero.

9. an option "user limits"

If you press this option you may set the lower and upper limit to any value between 0 and 300000 nanometers. These values are equivalent to having absolutely NO KNOWLEDGE of any thickness.

10. A submenu "layers" with lots of commands to delete, insert or switch layers. Especially important is the possibility to include "thick layers" = include the calculation of backside reflections.

### 9.1.2 Catalogues

In the menu Edit Structure you find a row "catalogues" for each layer. You may choose the **TYPE** of material like: glasses, semiconductors, metals etc. In the next row "materials" you may choose the actual material of your layer.

There are different catalogues for photoresists (for different companies like Clariant, Arch, Shipley, MRT and others).

You may add a new catalogue manually or use the menu Edit Refraction Index.

### 9.1.3 Materials

In the menu Edit Structure you find a row "materials" for each layer. You may choose the material itself: Si, GaAs, Ge etc.

In the previous row "catalogues" you first have to choose the TYPE of material of your layer (like "semiconductors"). There are different catalogues for photoresists (for different companies like Clariant, Arch, Shipley, MRT and others).

You may add a new material manually or use the menu Edit Refraction Index.

### 9.1.4 Thickness

ElliCalc uses values for the thickness between 0 and 300000 nm (=300 micrometers).

### 9.1.5 Estimates

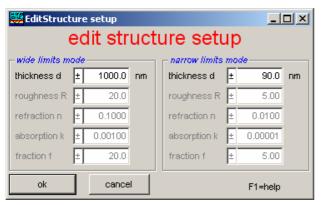
ElliCalc uses a maximum value for the estimates of 300000 nm (=300 micrometers).

In automatic mode it is **NOT** necessary to add values for the upper and lower estimate. You should give reasonable values for these limits in fitting mode as this influences the time for calculation considerably.

### 9.1.6 Fixed limits

If you fix a layer you force the upper and lower limit to have the same value as the thickness value. This means that the thickness of a fixed layer is regarded to be "well-known" = exact.

Example: thickness = 500 nm upper limit = 500 nm lower limit = 500 nm



### 9.1.7 Narrow Limits

If you click "narrow limits", ElliCalc uses rather narrow low and high limits range of about 100 nm above and below your thickness estimate (depending on the material of the layer)

Example1: thickness = 500 nm upper limit = 600 nm lower limit = 400 nm Example2: thickness = 3500 nm upper limit = 3600 nm lower limit = 3400 nm



If you need a larger range of limits you have to choose the options WideLimits or UserLimits (up to 300000 nm).

### 9.1.8 Wide Limits

To use this option you should consult the menu EditStructure \ Setup first: You have the choice between relative and absolute wide limits If you choose "relative wide limits" (e.g.  $\pm$ 500 nm and a thickness of 4000 nm), ElliCalc will search between 3500 nm and 4500 nm.

If you choose "absolute wide limits" (e.g. 1500 nm and 6000 nm and a thickness of 4000 nm), ElliCalc will search between 1500 nm and 6000 nm. The value of 4000 nm is of no importance in this case.

### 9.1.9 User limits

If you click "user limits", ElliCalc accepts your values for lower and upper limits (up to 300000 nm = 300 micrometers).

### 9.1.10 Number of layers

ElliCalc is doing all simulations with a maximum of 10 layers. An example of 3 layers:

	example of e laye									
🕎 E	dit layer structure						×			
File	Help									
	edit layer structure									
Air			_							
L3	semiconductors 📃 💌	Si_poly_50 🗸 🗸		13 0.08 ÷	100.0 🕂	140.0	narrow 🔻			
L2	others 💌	Cauchy 💌		x2 80.0 ÷	100.0 ÷	140.0	narrow 💌			
L1	oxides 💌	SiO2_(therm)		x1 410.0	500.0 ÷	590.0	narrow 💌			
LO	semiconductors 🗾 💌	Si(100) 💌	•							
Air	catalogue	material	d Rnkf	estimated lower limit	estimated value	estimated upper limit	limits mode			
			number of la	/ers: 3 📩						
	OK cancel									

### 9.1.11 Layer commands

in menu EditStructure there is a submenu "layers" which helps to insert, remove or shift layers within a stack.

	🚜 Eo	dit layer structure			×
l	File	Setup Layers He	elp.		l l
1		$\searrow$	ed	it layer structure	
l					
4					
	Air				
	L3	oxides	▼ SiO2_(CVD)	▼ └ └ └ d3 110.0 ÷ 200.0 ÷ 290.0 ÷ narrow ▼	- I
	L2	nitrides	▼ Si3N4	▼ ▼ □ □ □ □ d2 10.0 + 100.0 + 190.0 + narrow ▼	] [
1	L1	glasses	▼ BK7	thick layer [in mm] 0.525	
	LO	nitrides	▼ Si3N4	▼ ▼ □ □ □ □ □ d0 928.0 + 1000.0 + 1072.0 + user ▼	
	Air	catalogue	material	d R n k f estimated estimated limits mode lower limit value upper limit	
	ref	semiconductors	▼ Si(100)	number of layers: 3	
		OK cano	cel		



### application 1: show layer commands

if this option is activated a small list of commands is shown (like PageDown, PageUp, ...)

	💋 Er	dit laye	r struct	ire								×
F	File	Setup	Layers	Help								
			show	layer o	ommands	edit la	yer :	struc	ture			
			inser delet	: a laye : a laye e a laye a thick	rabove m							
	Air			_								
1	L2	oxides		-	SIO2_(CVD)	•	$\overline{}$	□ □ d2	110.0	200.0 ÷	290.0	narrow 🔻
1	L1	nitrides		-	Si3N4	- I	$\overline{}$	□ □ d1	10.0	100.0 ÷	190.0	narrow 🔻
١	LO	semicor	nductors	-	Si(100)	-						
1	Air	c	atalogue		material		dRn	k f	estimated lower limit	estimated value	estimated upper limit	limits mode
Ĩ	ref	semico	nductors	•	Si(100)	•	numb	r of layer	s: 2 📩			
- [		ок	i c	ancel								

		lower limit s	/alue 👘	upper limit
click on label to defselect layer	II r ESC € PageDown ≤	move selection up/down escape shift lauer upwards shift layer downwards	DEL INS	delete selected layer insert new layer above selected layer

### application 2: select a layer

To delete, insert or switch layers you first have to select a layer. You have 2 possibilities:

a. click on the label of the layer, e.g. L0 with a left mouse click

b. in submenu "layers" there is a command "select a layer"

ÆE	dit layer struct	ure			×
File	Setup Layers	Help			
			edit laye	r structure	
			select layer		×
			enter layernumber:		
Air					
L2	oxides	▼ SiO2_	i		Cancel 30.0 - narrow -
L1	nitrides	▼ Si3N4			30.0 narrow 🔻
LO	semiconductors		1		
	catalogue		9 1.		imits mode
Air	catalogue		acenar a ri	lower limit	value upper limit
ref	semiconductors	: 🔻 Si(100		11 move selection up/down	DEL delete selected layer
Ĺ.	ок 🗌	cancel	click on label to de/select layer	ESC escape PageDown shift lauer upwards PageUp shift layer downwards	INS insert new layer above selected layer

ł	🚜 E	dit layer structur	e	x
1	File	Setup Layers H	telp	
l			e	edit layer structure
I				
ł				
	Air			
	L2	oxides	SiO2_(CVD)	▼ ▼ □ □ □ □ □ d2 110.0 ÷ 200.0 ÷ 290.0 ÷ narrow ▼
1	L1	nitrides	✓ Si3N4	V 🗆 🗆 🗆 🖬 🛛 10.0 🗧 100.0 🗧 190.0 🗧 narrow 💌
•	LO	semiconductors	▼ Si(100)	<b>•</b>
	Air	catalogue	material	d R n k f estimated estimated limits mode lower limit value upper limit
	ref	semiconductors	V Si(100)	commands click on label ESC escape INS insert new layer above selected layer
		OK car	ncel	to de/select layer PageUp shift layer upwards PageUp shift layer downwards

### application 3: delete a layer

First select the layer that is to be deleted (see application 2). Then press the delete button on your keyboard

Or: select the layer and use the command "delete a layer" in submenu "layers"



### application 4: insert a layer (above another)

First select a layer (see application 2). Then press the insert button on your keyboard Or: select the layer and use the command "insert a layer above" in submenu "layers"

### application 5: switch layers

First select a layer (see application 2). Then press the PageUp or PageDown button on your keyboard

E	dit layer structure		<u>&gt;</u>
File	Setup Layers Help		
		e	edit layer structure
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	ntrides		▼ ▼ □ □ □ □ d1 10.0 → 100.0 → 190.0 → nerrow ▼
	semiconductors catalogue	Si(100) material	d B n k f estimated estimated limits mode
Air	catalogue	mavenar	lower limit value upper limit
ref	semiconductors	- Si(100)	cion o label ti move selection up/down DEL delete selected layer click on label ESC escape INS inset new layer above selected layer
	OK cance		click on label ESC escape INS insert new layer above selected layer to de/select layer PageDow shift layer downwards PageUp shift layer downwards
E F	dit layer structure		x
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		e	edit layer structure
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Air		-	
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	oxides -		V C C dt 110.0 200.0 290.0 narrow V
	semiconductors	Si(100)	
Air	catalogue	material	d R n k f estimated estimated limits mode lower limit value upper limit
ref	semiconductors	- Si(100)	cick on label ESC escape INS insert new laver above selected laver
	OK cancel		click on label ESC escape INS insert new layer above selected layer to de/select layer PageUp shift layer downwards

### 9.2 Main menu "Options"

### 9.2.1 Roughness

#### General:

It is quite difficult to measure interference if the substrate or the layers are rough, as the interference patterns get lost.

Example: Roughness is quite common for thick layers like 20 micrometers of photoresist, as the drying process is very critical and the shrinking of the resist does not lead to perfect surfaces. Roughness is also quite common for technical surfaces like aluminum or brass or steel that are to be covered with protection layers (like DLC=diamond like carbon layers).

### Methods:

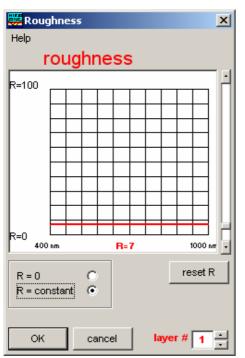
In ElliCalc internal mode (not in SCOUT mode!) an empirical method is implemented to deal with roughness:

#### 1. no roughness

No roughness is included in the calculation (=default).

#### 2. constant roughness

You will see some textboxes in the setup area which show "R-factors" for each interface. This value means a **percentage** of light that is regarded as lost at this interface. So there is no real physical roughness model. Such a physical model cannot be given as the typical size of the roughness is absolutely unknown. This means that even the scattering mechanism (Mie scattering, Rayleigh scattering etc) is unknown. There are some formulae in the literature but in our case these are not better than the above mentioned method of light loss via some empirical R-Factors.





An R-factor of R=0 means a perfect surface = no roughness

An R-factor of R=50 means a loss of 50% light at this interface.

There is no wavelength dependency of these empirical factors.

In the current version there is no wavelength dependency of these empirical factors.

#### constant roughness Attention:

You have to input roughness values in the setup roughness textboxes.

At each interface a certain amount of light is regarded as lost. This percentage has to be input via roughness textboxes in the setup area. These R-factors are not dependent on wavelength.

This algorithm does NOT manipulate measured data, but the measured amplitude might still differ considerably from the simulated amplitudes. This means that the fit procedure might still have problems to find a good solution.



# 10 Experimental setups and problems

### 10.1 General

### 10.1.1 Experimental setup

### Ellipsometer setup:

- carefully adjust the height of your stage to get maximized in intensity
- if your samples are not really perfectly plane thin about installing an autocollimator
- try to avoid stray light in the lab
- as your spot size is so small: pay attention on dust particles which may give wrong results

### 10.1.2 Maximum intensity

This value describes the maximum intensity in the spectrum of your lamp (can be easily checked in "auto intensity" mode).

If you use a double spectrometer there are TWO wavelengths corresponding to the sensitivities of the two spectrometers and your light source.

### 10.1.3 Polarization

In case of oblique incidence polarization plays an important role. In a vertical arrangement (like NanoCalc) the polarization does not play any role. "angle of incidence" is defined as the angle between the direction of incoming light and an axis vertical to the surface.

### 10.1.4 Signal to noise ratio

The intensity of your acquired signal depends on:

the adjustment of the lamp (see light source or ElliCalc-2000 manual) the integration time (see menu options) the number of averages (see samples to average in menu options) the diameter of the fiber the distance between fiber and wafer the sample itself

Do not extend the extraction limits into regions with a high signal-to-noise-ratio !

### 10.1.5Stray light

There is a slight risk to catch stray light from your laboratory lamps. Try to avoid this as much as. External light sources usually change and will produce errors.

### 10.1.6Fiber

Your ellipsometer may be equipped with different fibers with core diameters between 50 and 600 micrometers.

The spot size is directly proportional to the fiber diameter, of course the signal intensity decraeses quadratically.

Consult your hardware supplier.

### 10.1.7 Absorbing media

It is not too easy to measure absorbing media like polycrystalline silicon as their refractive and absorption indices usually depend strongly on preparation conditions.

Try to find good optical models for  $n(\lambda)$  and  $k(\lambda)$ .



### 10.1.8 Passwords

There are several passwords within ElliCalc:

As a start for user mode and administrator mode there is a password "admin". This password can be changed.

To change intercept, first coefficient and second coefficient and third coefficient (to recalibrate your own spectrometer) there is another password corresponding to the serial number of your Ocean Optics / Mikropack spectrometer. This number is displayed on a separate sheet or on the backside of your spectrometer system. If you could not find this serial number ask your hardware supplier...

### 10.1.9 Function buttons

If you click on the button F1, you get access to help functions.

If you click on the buttons **F2 - F7** different spectra or recipes together with their layer data are loaded for demonstration purposes.



# 11 Physical explanations

### 11.1 Refraction index and absorption indices

The refraction index n of a substance is defined as

$$n = \frac{C_{vacuum}}{C_{material}}$$

with c = speed of light

The absorption index k of a substance describes the absorption behavior of materials. Glasses and photoresists have negligible absorption in the visible range.

n and k are a function of the wavelength lambda:  $n = n(\lambda)$ . This phenomenon is called "dispersion".  $n(\lambda)$  and  $k(\lambda)$  are closely interrelated via the complex dielectric function  $\epsilon(\lambda)$ .

### 11.2 Cauchy coefficients

These coefficients empirically describe dispersion as a function lambda

$$n = n_1 + \frac{n_2}{\lambda^2} + \frac{n_3}{\lambda^4}$$
  $k = k_1 + \frac{k_2}{\lambda^2} + \frac{k_3}{\lambda^4}$ 

In many cases the 6 Cauchy coefficients are sufficient to describe the spectral behavior of resists, glasses etc. Normally ElliCalc uses "nanometers" as a unit dimension. If you add your own cauchy parameters in a .dat-file, pay attention on the correct dimension !! It is possible to use other dimensions within the software but not in the .dat-files.

Structure of a .dat-file:

SiO2_(therm)	name of the material
# this is my own comment 1	arbritrary comment (beginning with #)
# this is my own comment 2	
633,1.4570,0	lambda, n and k at 633 nm
150,900	measured data between these limits
Table	(or CAUCHY)
150,1.5510,0	n and k at 150 nm
151,1.5504,0	n and k at 151 nm
152,1.5491,0	n and k at 152 nm
153,1.5477,0	n and k at 153 nm
154,1.5464,0	n and k at 154 nm
and so on	

The first lines are not used by the software for calculation.

ATTENTION: Do not use any blanks in the name of the file !

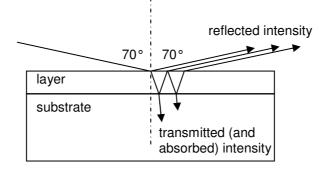
The third line (150,900) means that measured data are <u>measured</u> (=available) between these limits (LowerLimit=150 nm and UpperLimit=900 nm) and all extracted and displayed data (drawn in light Grey instead of black) between 900-1100 nm have NO meaning !!

### 11.3 Interference

The arrangement in the picture below shows the case of an oblique incidence.



The measurement of ellipsometry of thin films is a good example of an interference problem:



The incoming wave splits up in a reflected and a transmitted wave at each external or internal surface. The amplitudes of these partial waves depend on:

- 1.angle of incidence (if this angle is >0, then polarization plays
- an important role)

2.refraction index and absorption index of all layers

Now the superposition of ALL waves (with different phase relations, amplitudes) has to be done. If the layers are thin and flat you have to add **amplitudes** and not **intensities** (see your physics text book). So you may end up with "destructive and constructive interference": a positive amplitude and a negative amplitude may add up to zero. This is why your measured intensities usually have maxima and minima.



# 12 Thinfilm.ini

This \*.ini-file has to be located in the working directory of ElliCalc and should **NOT** be changed manually.

In emergency cases (= a corrupt file Thinfilm.ini) you may try to overwrite Thinfilm.ini with the default file Thinfilm.ini (on your CD).

ATTENTION: All files from CD-ROMs are write-protected. Click on the file name in Windows Explorer with your <u>right</u> mouse button and remove the write-protection.

### Section [UserEdits]

In the file Thinfilm.ini there is a section [UserEdits] very near to the beginning of the file. You may edit the file Thinfilm.ini with any text editor like notepad.exe or wordpad.exe (do not use Microsoft Word or similar programs). These entries are in part only for <u>special customers</u> and special equipment: they are NOT supported !!

#### Attention: be careful in editing this file ! Make a backup before you edit Thinfilm.ini !!

The section [UserEdits] contains some parameters which cannot be changed within the graphical user interface of ElliCalc because only special users need these features.

[UserEdits] WriteTmpFile=False WriteRefFile=False MinimumSearch=False AllowPixels=True Plot During Online=True Save\_During\_Mapping=False CCD\_StartCounts=0 WindowShift=175 AdjustRecipes=False Special FFTLayer=-1 Plot\_After\_FFT=False YScale\_FFTLayer=0 CsvExcelExport=xls CsvExcelSeparator=; CsvExcelNumberFormatter=. ExcelMargins LRTB=2;2;2;1 UseShutter=False SpecialLambda=-1 UseClipBoard=True HideElliCalc=False StopMappingStage=False SpectrometerSleepTime=30

#### WriteTmpFile:

if this flag is set to TRUE then ElliCalc will write a temporary file after each measurement. In rare cases the PC together with its network connection may be very slow and it is advisable to set the flag to FALSE. Then it will no longer be possible to use the feature "load last file" <u>WriteRefFile</u>

if this flag is set to TRUE then ElliCalc will write a file after each reference measurement. In rare cases the PC together with its network connection may be very slow and it is advisable to set the flag to FALSE. Then it will no longer be possible to use the feature "load last reference" <u>MinimumSearch</u>

this is reserved for a special customer (using antireflective coatings) <u>AllowPixels</u> If you disable this feature by setting the flag to FALSE it will not be possible to use the pixel mode. You gain some speed as no recalculation for pixels is done with each measurement. <u>Plot During Online</u> if you set this flag to FALSE then you gain some speed during online measurements as no plots are shown Save During Mapping

allows to save all spectra during mapping (time-consuming !)



### Online StartCounts

some spectrometers need a certain number of calls to the CCD pixels before they give stable results. If you set this number to any value less than 10 (e.g. Online\_StartCounts =5) you will have to wait until 5 dummy measurements have been done. If you use a short integration time it is recommended to use values of 5-10. If you use a longer integration time and you do not want to wait for some seconds it is recommended to set the value to zero (but be aware that the first 1-5 measurements may not be completely correct)

#### <u>AdjustRecipes</u>

True: the main menu will contain a possibility to change a certain parameter in ALL recipe or ini-files simultaneously

#### Special FFTLayer

for NanoCalc and special customer only

if any valid layer number is set to some number <> -1 (=default), the FFT result will be changed to get the thickness result of this special layer and not the total sum of all layers (ask your software supplier for details).

There is also an application to extract the refraction index instead of thickness (ask your software supplier for details).

Plot After FFT

for NanoCalc and special customer only

If this variable is set to FALSE only the FFT peak wil be plotted and not the extracted (=simulated) curve <u>YScale\_FFTLayer</u>

for NanoCalc and special customer only

this number gives a zoom factor for the main FFT peak (it can be changed within the software by pressing the + and - buttons)

<u>csvEXcelExport</u>

you may enter csv oder xls (example: csvEXcelExport=csv). Csv is the well-known "comma separated value" format.

csvEXcelSeparator

here you may enter the separator for the csv-format, like ";" oder"," (example: csvEXcelSeparator=;) csvExcelNumberFormatter

here you may enter the number formatter for the csv-format, like "," oder"." (example:

csvExcelNumberFormatter=.)

ExcelMargins LRTB To print Excel sheets: this sets Left, Right, Top,Bottom

UseShutter

If you need control over the shutter of the light source (True/False)

SpecialLambda

for NanoCalc and special customer only

UseClipBoard=True

To avoid copying measured data to clipboard

HideElliCalc

To avoid ElliCalc in windows taskline

StopMappingStage

To enable/disable the xy-motors after 1 step

<u>SpectrometerSleepTime</u>

A time in minutes. After this time the spectrometer is asked up to 10 times to "reactivate" it.



# 13 Appendix A

### 13.1 Installing and changing the settings on a A/D converter and Interfaces

This section covers the basic installation instructions for our A/D converters: ADC500<sup>1</sup>, ADC1000, DAQ700 and USB2000, because A/D converter installation goes hand-in-hand with software installation. The A/D converters we offer are:

**ADC1000 ISA-BUS A/D CONVERTER** is a high-speed, 12-bit, 8-channel, single-ended, half-length card that fits into a slot in a desktop PC and has 1000 kHz sampling frequency. **DAQ-700 PCMCIA A/D CONVERTER** from National Instruments is a 12-bit, 16-channel, single-ended card that fits into a credit card-size slot in a notebook PC and has 100 kHz sampling frequency.

**USB Interface** is a universal Serial Bus Interface for ATX-Pentium Computers with Windows 98 and 2000. The AD/Converter 12 Bit 1 MHz can run with a minimum integration time of 3ms and is integrated in the ElliCalc-2000-System. The Minimum Data Transfer Time from ElliCalc-2000-System to PC is 25ms.

### 13.1.1 ADC1000 ISA-bus A/D Converter

The **ADC1000 ISA-BUS A/D CONVERTER** is a 12-bit, 8-channel, single-ended A/D card that connects our spectrometers to desktop PCs. The AVS-PC2000 has a 2048-element linear CCD-array fiber optic spectrometer mounted onto an ADC1000. This sturdy combination fits easily into a slot in the PC. The following are directions for installing your ADC1000 and PC2000. Because A/D converter installation goes hand-in-hand with software installation, you will find directions for installing ElliCalc Spectrometer Operating Software included in this section as well. Each device in or connected to your computer is assigned specific settings; it's similar to giving each device its own name so that your computer will know what to call and how to recognize the device. In order for your ADC1000 or AVS-PC2000 to work as a device in your computer, it has to be assigned a Base Address setting and an IRQ setting. The default settings for each are:

# Base Address (I/O Range):768 decimal (300 hexadecimal)Interrupt Request (IRQ):07

These default values are set on the A/D converter. There are dip switches on the A/D board and their positions determine the values. These default values are set in the operating software as well. Most of the time, these default settings will work with your computer. However, if you have many devices installed in your computer, you may have a conflict; other devices may be using these settings. If there is a conflict with another device in your computer, you must change the positions of the switches on the A/D board. For the ADC1000 and PC2000, there is only one bank of switches on the A/D board: the Base Address may be changed via the first 6 switches and the IRQ may be changed via the last 3 switches. To first check your computer to see which settings are available, follow the instructions for the Windows system that you use.

<sup>&</sup>lt;sup>1</sup> Discontinued since August 2000



### 13.1.1.1 ADC-1000 installation

### For Windows XP Users: Find Available Base Address and IRQ Settings

Go to **Start | Programs | Administrative Tools (Common) | Windows NT Diagnostics**. In the "Windows NT Diagnostics" dialog box, click on the **Resources** tab.

Select the **IRQ** button. Find an available IRQ -- a number unassigned to a device.

Select the **I/O Port** button. Find an available I/O Range (Base Address) -- a number or range of numbers unassigned to a device. (The number is in hexadecimal.)

Note these available settings. When you first run ElliCalc, you must enter these values in the "Setup Hardware" dialog box. With Windows NT, devices cannot share IRQ 's; each device must be assigned a unique IRQ.

<b>Bestand</b> Hel	NT diagnostische gegevens p	- \\NT_WORKS	T_07
Versie Servic	Systeem Beeldscherm ces Bronnen	Stations Omgeving	Geheugen Netwerk
		HAL-bronner	n opnemen 🗖
1R0 01 03 04 06 11 12 14 15	Apparaat (6042pt Serial Serial Foppy 2023 Hol42pt atapi atapi	Bus 0 0 0 0 0 0 0 0 0	Type Isa Isa Isa Isa Isa Isa Isa
IBQ	I/ <u>O</u> -poort <u>D</u> MA	Geheugen	Apparaten
<u>E</u> igenscha	appen Vernieuwen	Afdrukken	OK

Versie Systeem Beeldscherm Stations Geheuge Services Bronnen Omgeving Netwerk						
HAL-bronnen opnemen						
Adres	Apparaat	1	Bus Typ	ie 🔺		
0060 - 0060	i8042prt		D Isa			
0064 - 0064	i8042prt		D Isa			
0170 - 0177	atapi		D Isa			
01CE - 01CF	VgaSave		D Pci			
01F0 - 01F7	atapi		D Isa			
02F8 - 02FE	Serial		D Isa			
0376 - 0376	atapi		D Isa			
0378 · 037A	Parport	1	D Isa			
03B0 - 03BB	atirage		1 Pci			
03B0 - 03BB	VgaSave		D Pci			
03C0 - 03DF	atirage		1 Pci			
03C0 - 03DF	VgaSave		D Pci			
03F0 - 03F5	Floppy		D Isa			
03F6 - 03F6	atapi		D Isa			
03F7 - 03F7	Floody		D Isa	-		
IBQ	1/Q-poort	DMA Geh	eugen i	Apparaten		



### 13.1.1.2 ADC-1000 hardware installation

Installation of the ADC1000 is similar to that of any PC card installation:

Ground yourself to the computer chassis or power supply.

Turn off and unplug the computer. Then take off the computer cover.

Remove the ADC1000 from its static-shielded bag.

If necessary, change the position of the switches on the A/D board. Position the switches to match the available settings you found in the previous section -- numbers not being used by other hardware devices. The Base Address may be changed via the bank of switches labeled SW1 and the IRQ may be changed via the bank of switches labeled SW2.

See Table below for switch setting positions

Find an open ISA-bus slot and remove the slot protector.

Insert the ADC1000 into an available expansion slot on the motherboard connector by *gently* rocking the card into the slot. Make sure the ADC1000 is fully seated in the motherboard before screwing the tab on the ADC1000 to the computer.

Reinstall the cover and reconnect the computer power cord.

For the ADC-1000: Connect the D37 end of the interface cable to the ADC1000 and the D25 end of the interface cable to the spectrometer.

### Base Address (SW1)

To change the Base Address settings on the ADC1000 board, see the bank of 6 dip switches labeled SW1. Switches in the ON position have a value of zero. Switches in the OFF position have the decimal values shown. The Base Address is the sum of the values of the switches. In the default setting, switches 5 and 6 are added to give a total of 768. A few of the many combinations for Base Address settings are below.

### Example: 768 decimal = Hex300 = 0x300 (Default Setting)

Switch #	1	2	3	4	5	6
on						
off						

### Example: 784 decimal = Hex310 = 0x310

Switch #	1	2	3	4	5	6
on						
off						

#### Example: 800 decimal = Hex320 = 0x320

Switch #	1	2	3	4	5	6
on						
off						

#### Example: 816 decimal = Hex330 = 0x330

Switch #	1	2	3	4	5	6
on						
off						

Switch is in the on-upward position



IRQ Interrupt Request Settings (SW2)

To change the IRQ settings on the ADC1000/AVS-PC200 board, see the bank of 3 dip switches labeled SW2. In the default setting, the IRQ is set to 7. Other combinations for IRQ settings follow.

### IRQ 7 (Default Setting)

Switch #	7	8	9
on			
off			

### <u>IRQ 3</u>

Switch #	7	8	9
on			
off			

### <u>IRQ 4</u>

Switch #	7	8	9
on			
off			

### <u>IRQ 5</u>

Switch #	7	8	9
on			
off			

### <u>IRQ 9</u>

Switch #	7	8	9
on			
off			

### <u>IRQ 10</u>

Switch #	7	8	9
on			
off			

### <u>IRQ 11</u>

Switch #	7	8	9
on			
off			

Switch is in the on-upward position

-1			
- 1			
- 1			
- 1			



#### Setup Hardware Dialog Box

The first time ElliCalc is started, the hardware needs to be set up correctly. Clicking the menu "screen-spectrometer datahardware" can do this. The parameters in this dialog box are usually set only once -- when ElliCalc is first installed and the software first runs.

Under **Spectrometer Type**, choose your spectrometer. Under **A/D Converter Type**, choose ADC-1000/PC2000. Choose **Base Address** as selected in the previous section. Choose **IRQ** as selected in the previous section. For your setup, only these parameters apply to your system. (Ignore the other settings; they apply to other A/D converters.) Click **O**K.

#### Configure Hardware

Version:	3.00.05	
Spectrometer Type S2000/PC2000 A/D Converter Type	S2000E First Pixel 950	
AD C1 000/PC2000 Base Address (I/O Range) 768 (0x0300)	IRQ (Interrupt Request)	
Serial Port           2           SAD500 Pixel Resolution		
<u>0</u> к	<u>C</u> ancel	

### 13.2 ElliCalc-2000 Systems with ADC1000-USB Installation

The ElliCalc-2000 Systems delivered from October 2001 and later have an internal AD-Converter as standard and the communicates between computer and ElliCalc works via USB-Serial Interface. This AD-Converter is called ADC-1000-USB. (AD-Converter, 1MHz, USB Interface)

After installing the ElliCalc Software, connect the ADC1000-USB with the USB cable delivered with the system and insert the cable to your computer's USB port. If you use Windows2000, an error dialog may appear caused by the missing file ezusb.sys. In that case, please refer to the section "Troubleshooting installation ADC1000-USB with Windows2000" on how to solve this problem.

Setup Hardware Dialog Box

When the ElliCalc Software runs the first time, the hardware needs to be set up correctly. Go to the Setup > Hardware menu. The parameters in this dialog box are usually set by the user only once when the ElliCalc software first runs.

Under Spectrometer Type, choose S2000 (see picture1)

Under A/D Converter Type, choose ADC-1000-USB (see picture2)

Choose the USB Serial Number adressed to the ElliCalc System (see picture3) Click OK.



### picture1 Configur

cture1	picture2	pi
onfigure Hardware 🛛 🗐	Configure Hardware 🔠	Ca
Ocean Optics Windows Device Driver 32-bit Version: 4.00.02 Spectrometer Type S2000/PC2000/HR2000 S2000/PC2000/HR2000 S2000/PC2000/HR2000 S20008T S1024DW USB Serial Number First Available ADC1000-USB	Ocean Optics Windows Device Driver 32-bit Version: 4.00.02 Spectrometer Type S2000/PC2000/HR2000 ▼ A/D Converter Type ADC1000-US8 ▼ USB2000/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR2000 ADC200/HR200 A	
<u>Q</u> K <u>C</u> ancel		

#### picture3

Configure Hardware	ð
Ocean Optics Windows Device Driver 3	2-bit
Version: 4.00.02	
Spectrometer Type	
S2000/PC2000/HR2000	
A/D Converter Type	
ADC1000-USB	
USB Serial Number	
First Available ADC1000-USB	
AD000213	
<u> </u>	

#### Specifications

Туре	USB universal serial Bus
A/D resolution, sampling frequency	12 bit @ 1 MHz integrated in ElliCalc-2000-System
Channels	16-channel single ended, 8-channels differential
Interface cable	USB interface cable (Standard)
Data Transfer rate	Min. 25ms (integration time 3 ms)
Software requirements	WIN XP
Computer requirements	ATX-IBM compatible with Pentium or better microprocessor, 1 GB RAM and WindowsXP

#### Trouble Shooting with ADC-1000-USB 13.2.1

If you accidentally connected the ADC-1000-USB to your PC before installing the ElliCalc Software, or if you use an older version of the ElliCalc Software, you will get a message that Windows has not installed a driver for the device. To rectify an incorrect installation follow these steps:



# 14 APPENDIX B

### 14.1 ElliCalc-Quick-Setup

This Appendix helps you step by step to get a first measurement. This description is using the reference stepwafer from Mikropack, SiO2-Steps on Si-Wafer.

Install the ElliCalc software and AD-Converter (see Appendix A)

Start the computer, the power supply for the motors (black box) and the ellipsometer itself (front side)

Plug-In the USB-Cable (or blue AD-Cable), then install the fibercable between the spectrometer and the lightsource.

Put the sample (step-wafer ?) on the chuck

Start the ElliCalc software (WITH a reflecting sample on the chuck !!)

Load a SCOUT layer recipe that is good for your sample (files\load layer recipe)

Click "Init" and wait until this operation is finished (about 15 seconds)

Maximize signal intensity (continous button) by adjusting stage height

Eventually re-adjust intensity by pressing "auto intensity"

Click "Measure" During the measurement (some seconds) you see the measured raw data and finally the Psi/Delta spectrum Maximize signal intensity (continous button) by adjusting stage height

Eventually re-adjust intensity by pressing "auto intensity"

Click "Measure" A result is displayed in the upper right half of the screen

Now you are ready !!!



### 15. Lamp Replacement

Replacement of Halogenmodule SpecEI-2000-VIS/NIR-BM

General information for the use of halogen light bulbs.

Lifetime is approx. 1000h

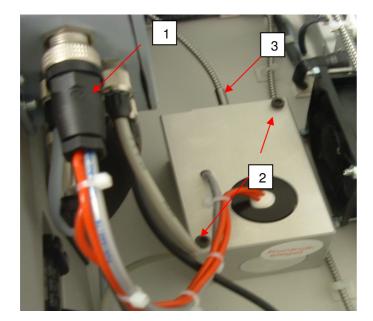
The warm-up time is within seconds for measurement  $\geq$  50nm (500Å). For high performance and  $\leq$  50nm (500 Å) wait approx. 10 min for lamp stabilization)

To save lifetime you can switch on and off the light source by using Light source switch for every Measurement campaign(it is not necessary to let run the light bulb all the time)

### Replacement



- 1. Shut down all power
- 2. Disconnect the unit from the power supply
- 3. Open the black SpecEl housing by removing the screws (5x)



- 1. Unplug the HL-Module connector
- 2. Unscrew the two HL-Module screws
- 3. Unplug the fiber very carefully
- 4. Replace complete SpecEl-2000-VIS-NIR-HL Module
- 5. Do all steps again in reverse direction
- 6. Calibrate the ellipsometer again.

Order Information:

SpecEI-2000-VIS/NIR-BM SpecEI-2000-VIS/NIR-B (Halogenlightsource module for replacement (Replacement of the bulb at the supplier or factory side)



### 16. Warranty

Mikropack GmbH warrants to the Original User of this instrument that it shall be free of any defects resulting from faulty manufacture of this instrument for a period of 12 months from the original data of shipment.

This instrument should not be used for any Clinical or Diagnostic Purposes. Data generated is not warranted in any way by Mikropack GmbH. Any defects covered by this Warranty shall be corrected either by repair or by replacement, as determined by Mikropack GmbH.

There are no warranties which extend beyond the description.

This Warranty is in lieu of, and excludes any and all other warranties or representation, expressed, implied, or statutory, including merchantability and fitness, as well as any and all other obligations or liabilities of Mikropack GmbH, including, but not limited to special or consequential damages. No person, firm, or corporation is authorized to assume for Mikropack GmbH. Any additional obligation or liability not expressed provided for herein except in writing duly executed by an officer of Mikropack GmbH.

### Warranty Handling

1. Clear with your local distributor the problem or fault.

2. In case of warranty your local distributor will give you a RMA number.

3. Send your instrument free of charge and insured to your local distributor.

4. Your distributor will inform you on delivery time. If there is repair out of warranty you will be informed about repair cost. The system will be on hold till you have officially ordered the repair.

The system will be send back to you free of transport cost and insured (in case of warranty)

### 17. Contact

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